

ECE520 – VLSI Design

Lecture 1: Introduction to VLSI Technology

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Office: ECE Bldg. 230B

Office hours: Wednesday 2:00-3:00PM or by appointment

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Course Objectives

- ❑ We will focus mainly on CMOS integrated circuits
- ❑ There will be a design project assigned including:
 - Schematic design using S-Edit
 - Spice simulations and design verification
 - Layout design using L-Edit (including LVS and DRC)
 - Circuit extract and spice simulation (again)
- ❑ Project will be done by groups of 3-4 students
- ❑ Project grade will be based on:
 - Quality of report
 - Performance (speed/delay)
 - Power dissipation
 - Layout area
- ❑ There will be a 10% extra credit for any design that beats certain criteria for layout area, performance, or power consumption

Textbook and References

❑ Main textbook:

- “Digital Integrated Circuits” by J. M. Rabaey et al. (2nd edition)

❑ Other reference books:

- “Physical Design of CMOS Integrated Circuits Using L-Edit” by J. Uyemura
- “Design of High-Performance Microprocessor Circuits”, by A. Chandrakasan

❑ Lecture Notes: combination of slides and discussions

- Slides will be posted on the class webpage
- Class webpage: www.unm.edu/~pzarkesh/ECE520

❑ Reference papers posted on the class webpage

Grading Policy

- ☐ **Your grade in the course will be comprised of:**
 - Homework (25%)
 - Project (25%)
 - Midterm Exam (25%)
 - Final Exam (25%)
- ☐ **Final letter grade will be based on curve and class performance**
- ☐ **No makeup exam**

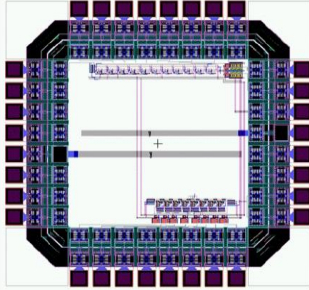
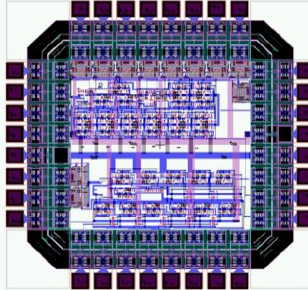
Homework Policy

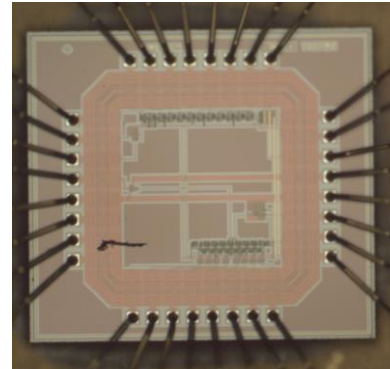
- ☐ **Homework will be on weekly basis and is setup for the project**
 - Learn CAD tools and basic circuits
 - Require lab work
- ☐ **Solutions will be posted on the class website as soon as I can**
- ☐ **Late homework and projects have 20% per day credit penalty**

Class Project & Tools

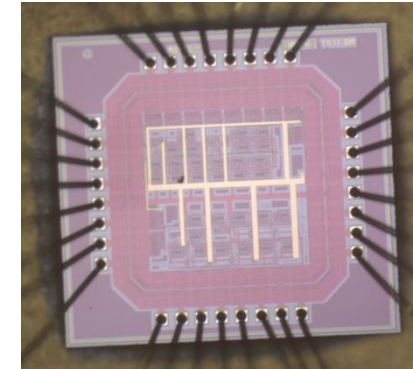
- ☐ **Use of CAD tools will be required for most assignments. Get yourself familiarized with the tools from today!**
- ☐ **This is a project oriented course. Be prepared for extensive lab work!**
- ☐ **We will be using L-Edit for our VLSI project**
 - all Tanner tools including L-Edit, S-Edit, T-SPICE, LVS, and W-Edit are installed on all machines in ECE 211 Lab
 - The tools can also be installed on your own computer for the project use
 - for more information about these tools, please visit class website
- ☐ **We will be using ON Semiconductor 0.5um for our project**
 - Selected projects will be submitted for manufacturing by MOSIS
 - for more information about this process please visit <https://www.mosis.com/vendors/view/on-semiconductor/c5>

Projects Manufactured by MOSIS in 2009

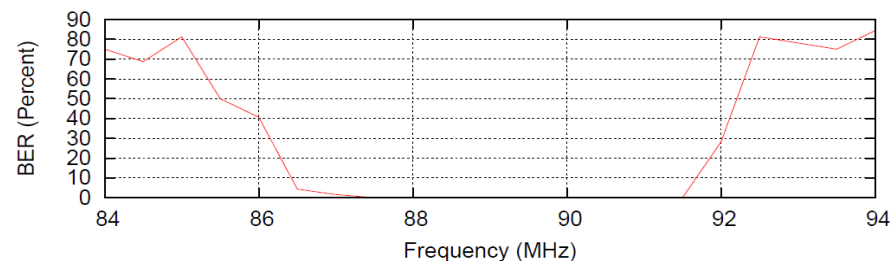
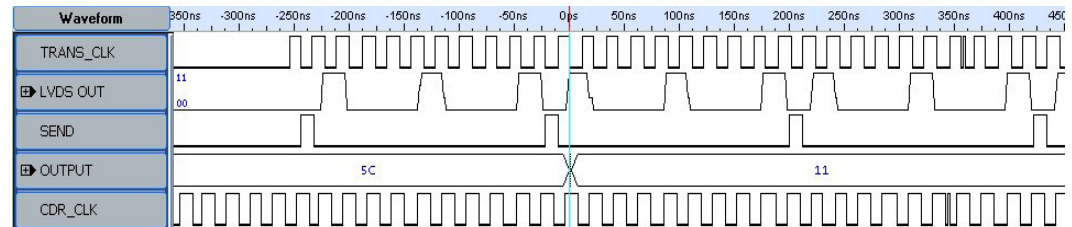
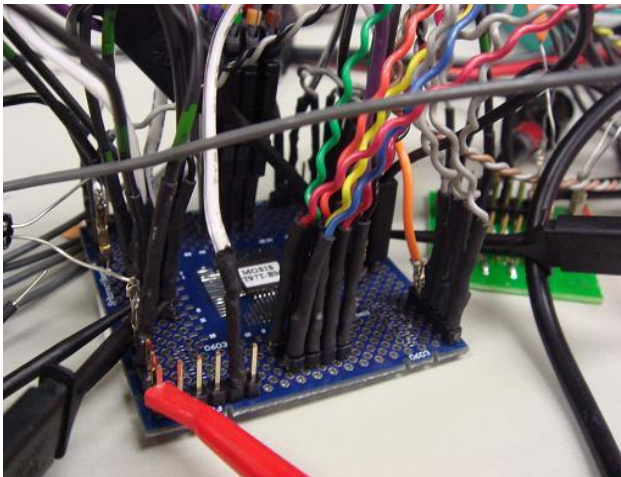
Test Chip 1	Test Chip 2
Thomas Leboeuf John (Colby) Hoffman	Kevin Fox Srinivasan Sridhar Shawn Levesque
	



Test Chip 1

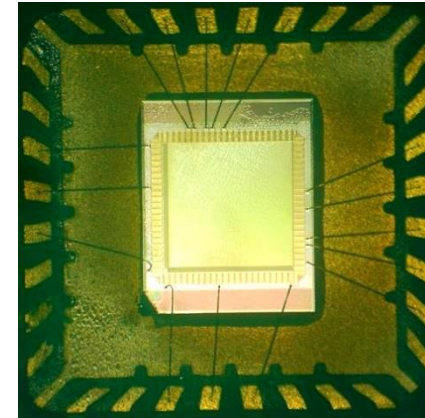
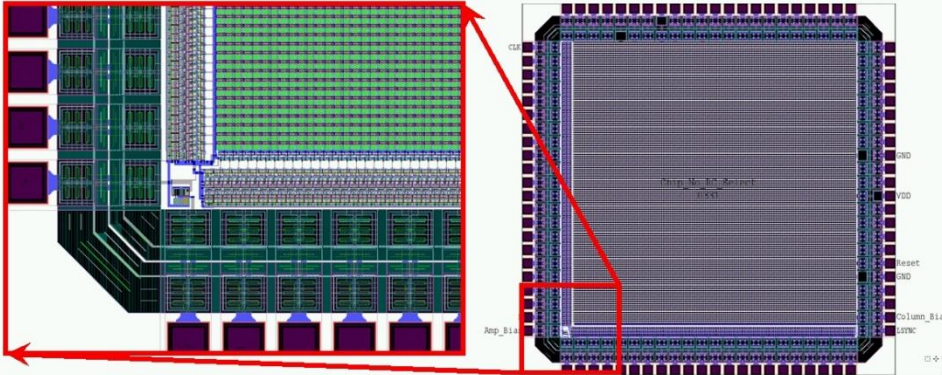


Test Chip 2

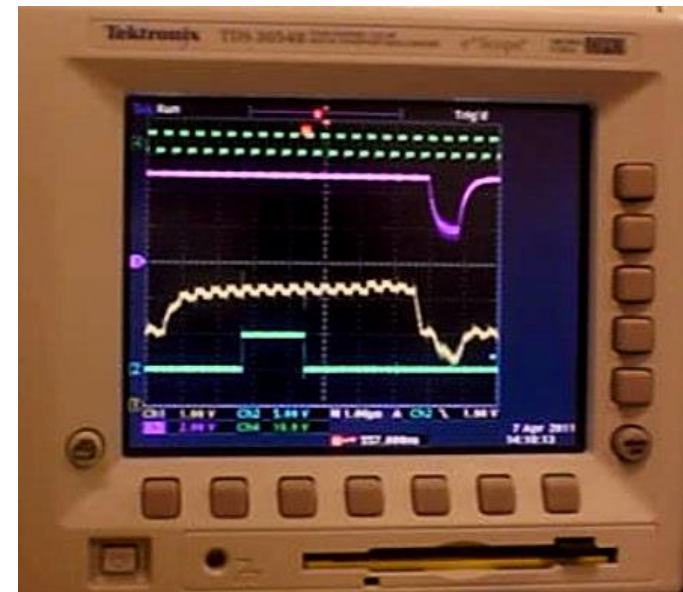
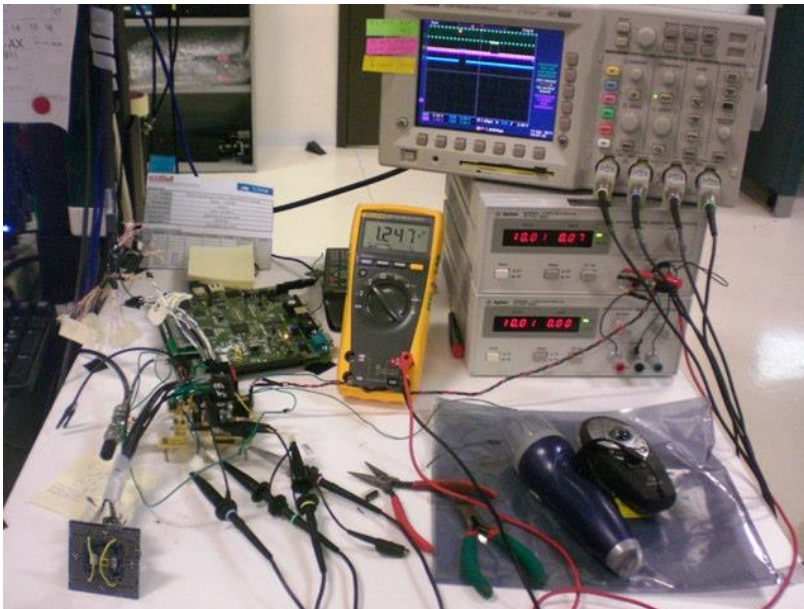


Projects Manufactured by MOSIS in 2010

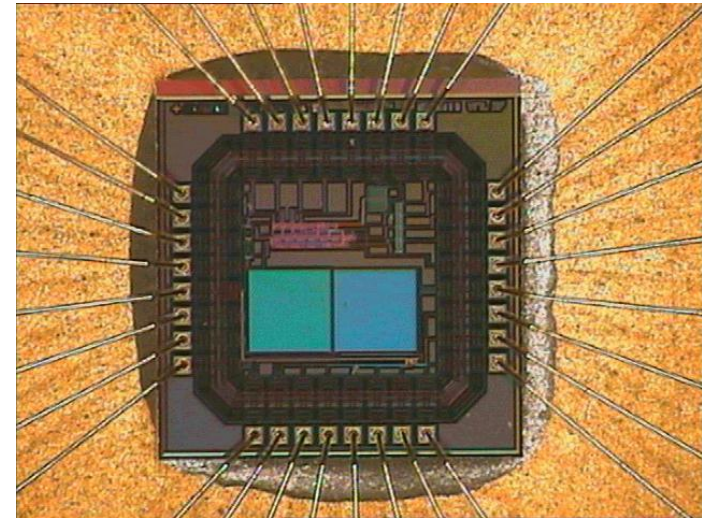
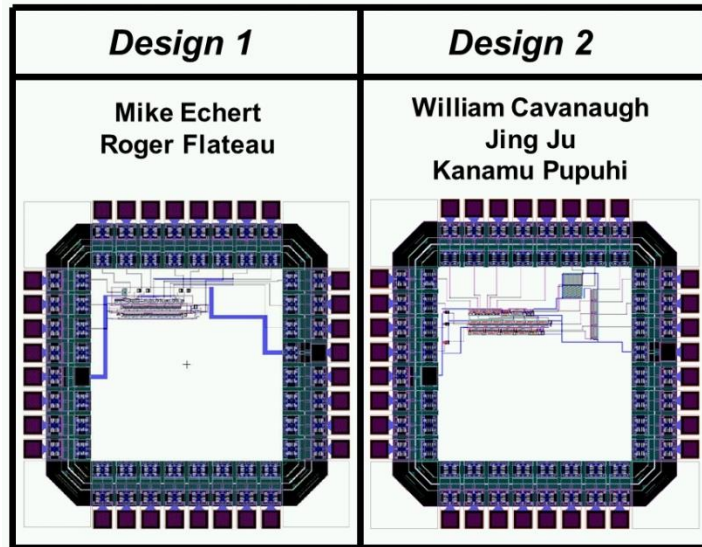
Selected Design By: Cesar Mendez Ruiz and Ethan Tanner



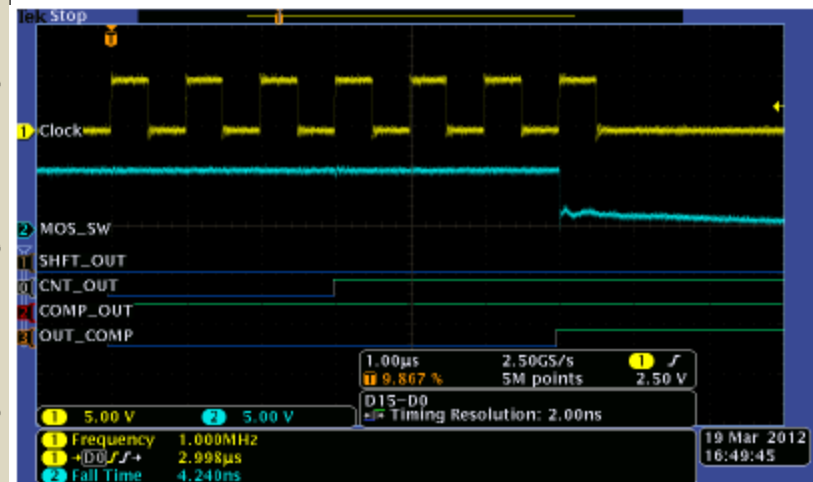
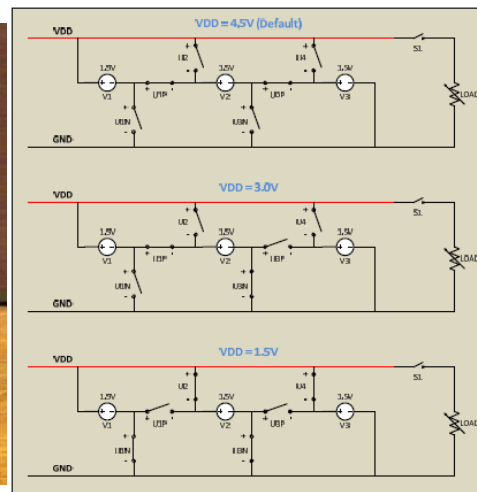
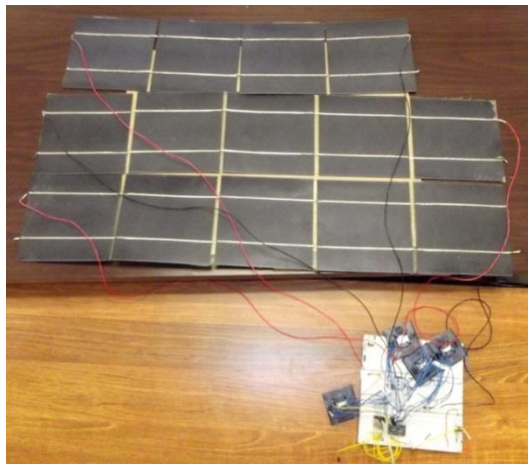
Die Photograph of the Test Chip



Projects Manufactured by MOSIS in 2011

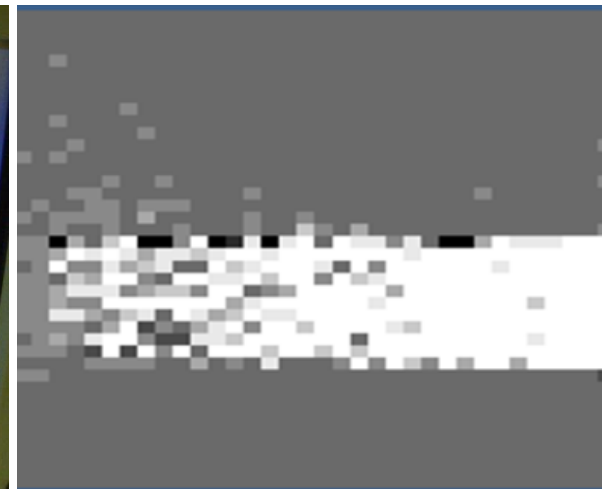
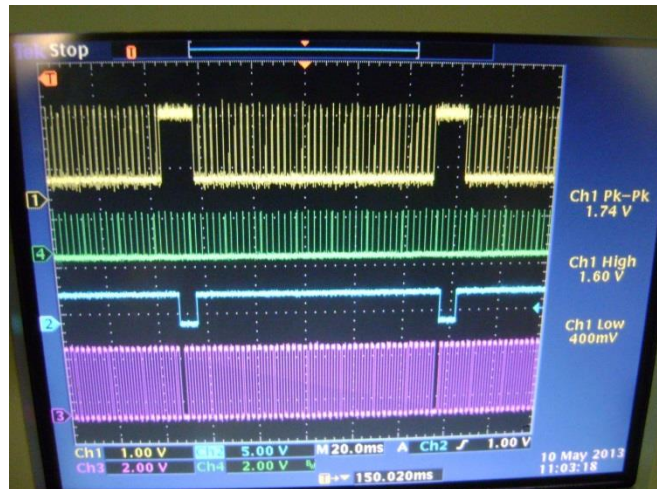
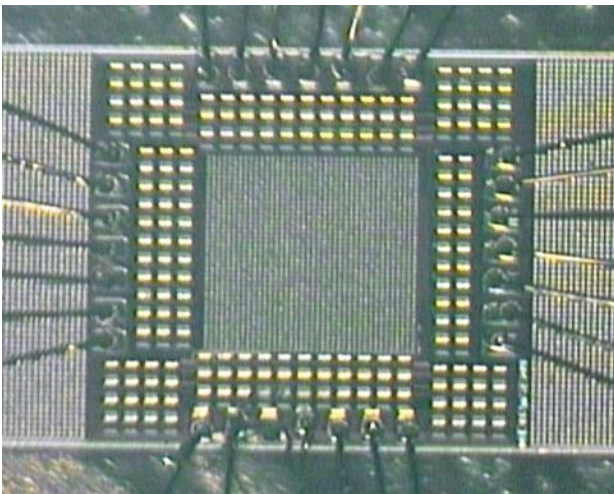
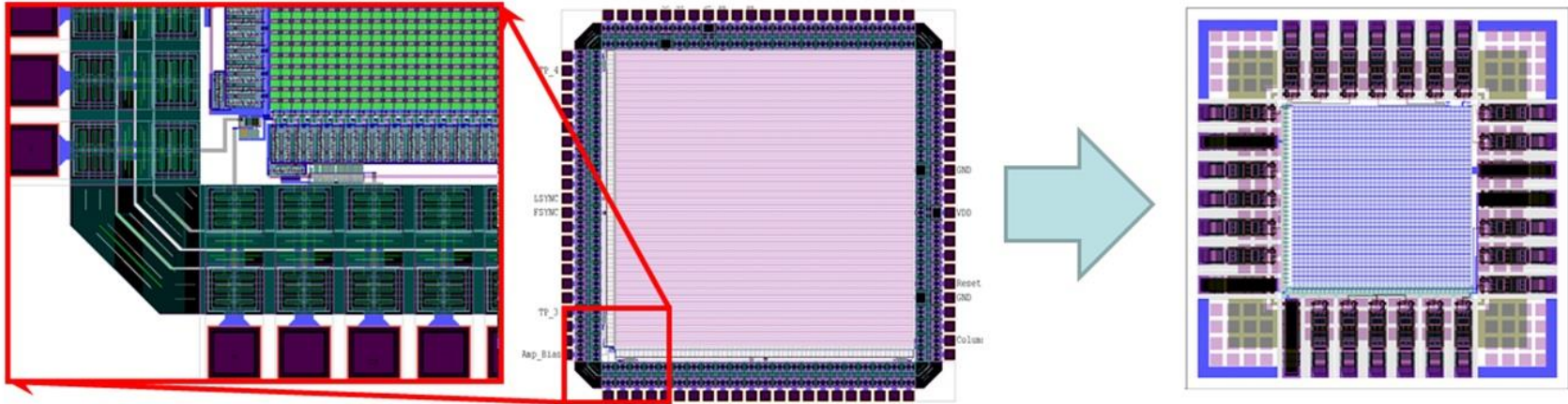


Die Photograph of the Test Chip 2

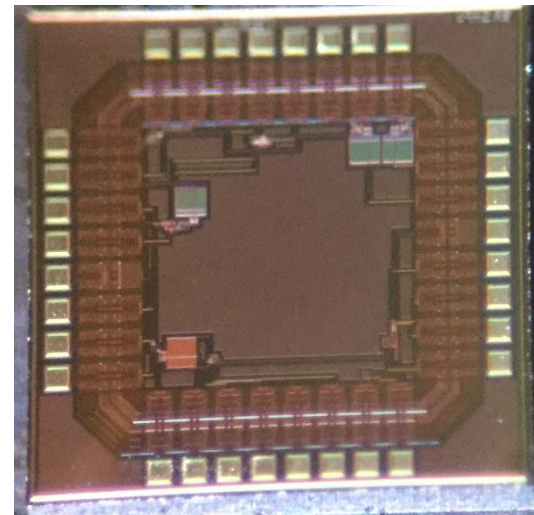
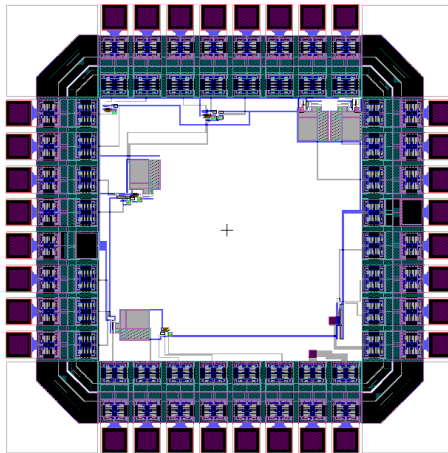
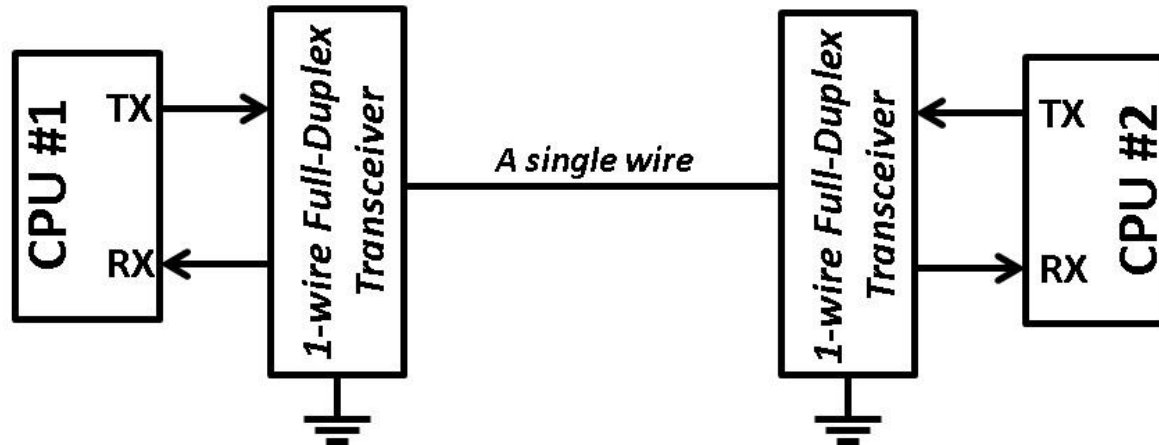


Projects Manufactured by MOSIS in 2012

Selected Design By: Javad Ghasemi



Projects Manufactured by MOSIS in 2019



Class Schedule

Warning: Lecture schedule subject to change!!

Date	Day	Topic	Reading/Coverage
January 21	Tue	Introduction to VLSI Technology	1.1-1.3
January 23	Thr	Basic MOS Physics I (static)	3.2
January 28	Tue	Basic MOS Physics II (dynamic)	3.3
January 30	Thr	Device Scaling Issues	3.4-3.5
February 4	Tue	Device Scaling Issues - cont.	3.4-3.5
February 6	Thr	Basic CMOS Inverter	5.1.4
February 11	Tue	Basic CMOS Inverter - cont.	5.1-5.4
February 13	Thr	Dynamic Behavior of CMOS Inverter	5.4-5.6
February 18	Tue	CMOS Manufacturing Process	2.1-2.3, 2.4 (review), 2.5
February 20	Thr	Interconnect Manufacturing & Modeling	4.1-4.5
February 25	Tue	Design Rules	2.3, insert A
February 27	Thr	Layout Techniques & L-Edit Demo	handouts
March 3	Tue	Combinational Static Logic	6.1-6.2
March 5	Thr	Gate Sizing (Inverter Chain)	5.4
March 10	Tue	Gate Sizing (Inverter Chain) - cont.	5.4
March 12	Thr	Midterm Exam	-
March 17	Tue	Spring Break	-
March 19	Thr	Spring Break	-
March 24	Tue	Logical Effort	6.1 - 6.2
March 26	Thr	Logical Effort - cont.	6.1 - 6.2
March 31	Tue	Pseudo Logic and Pass-Transistor Logic	6.2
April 2	Thr	Project Review	-
April 7	Tue	Dynamic Logic	6.3
April 9	Thr	Advanced topics: Power Reduction	Handout
April 14	Tue	Sequential Logic	7.1-7.2
April 16	Thr	Sequential Logic - cont.	7.1-7.2
April 21	Tue	Timing Issues	10.1-10.2
April 23	Thr	Clock Distribution - PLL	10.3
April 28	Tue	Power Distribution & I/O Circuits	9.1-9.4
April 30	Thr	Memories	12.1-12.2
May 5	Tue	Nonvolatile Memories	12.2
May 7	Thr	SRAM Memories & Review for Final	Project Due
May 12	Tue	Final Exam (12:30-2:30PM)	-

Reading Assignment

- ❑ Today we will review Chapter 1 and some more
 - Introduction and history
- ❑ Our next class will be on Chapter 3 (MOS Physics)
 - Skim through Diodes but focus on Section 3.2.3 (diode transient behavior)
 - Study Section 3.3 (MOS transistor) thoroughly
- ❑ We will get back to Chapter 2 (Manufacturing Process) later

VLSI Design Flow

- ❑ **The goal of VLSI designers is to design a circuit block that meets the following objectives:**
 - Maximize speed or performance
 - Minimize power consumption
 - Minimize area
 - Maximized robustness

- ❑ **Methods that they use are:**
 - Circuit design, transistor sizing
 - Use of new architectures, clock gating, etc
 - Choice of circuit style, efficient layout design
 - Interconnect design and optimization

VLSI Design Approaches

- ❑ Gate Arrays (Old technology, but still attractive)**
 - Pre-fabricated chips containing transistors and local wiring
 - Upper level wires added to implement design
 - Rapid design, but very sub-optimal, slow, and usually high power consumption

- ❑ Standard Cells (Used for ASIC design)**
 - Cells in a library with fixed sizes
 - Cells pre-characterized for delay and power
 - Design is fast and layout is done automatically
 - Better performance, in the range of several 100's MHz

- ❑ Custom Design (Used for Microprocessor design)**
 - Optimal circuit design and sizes
 - Extensive design verification required
 - Slowest, but densest layout design
 - Best performance, in the range of 1-5 GHz

VLSI Design Tools

☐ **Synthesis**

- Logic, micro-architecture, automatic physical generation

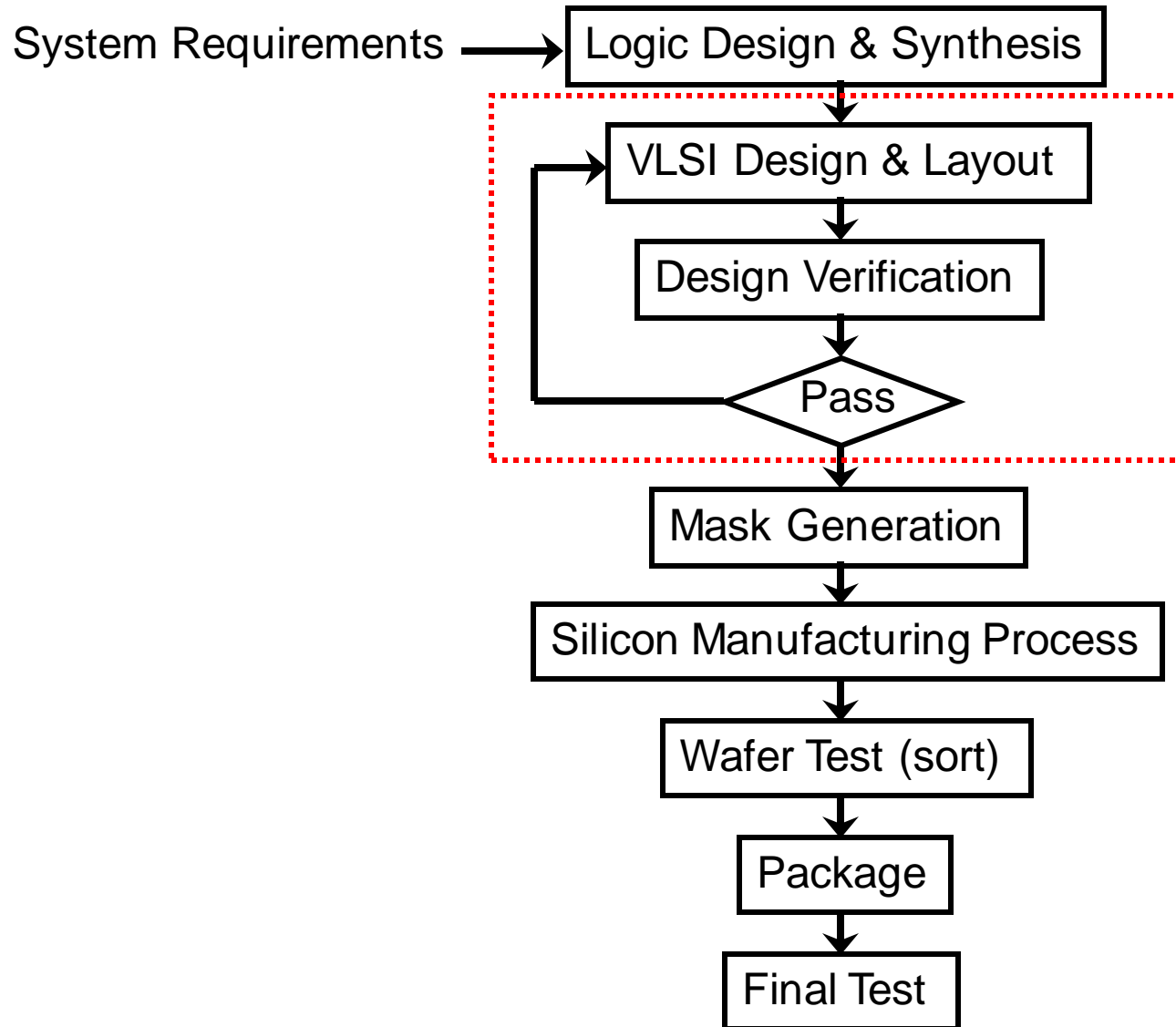
☐ **Static Analysis**

- Design rule checking (DRC)
- Circuit extraction
- Timing analysis
- Test generation (ATPG)

☐ **Dynamic Analysis**

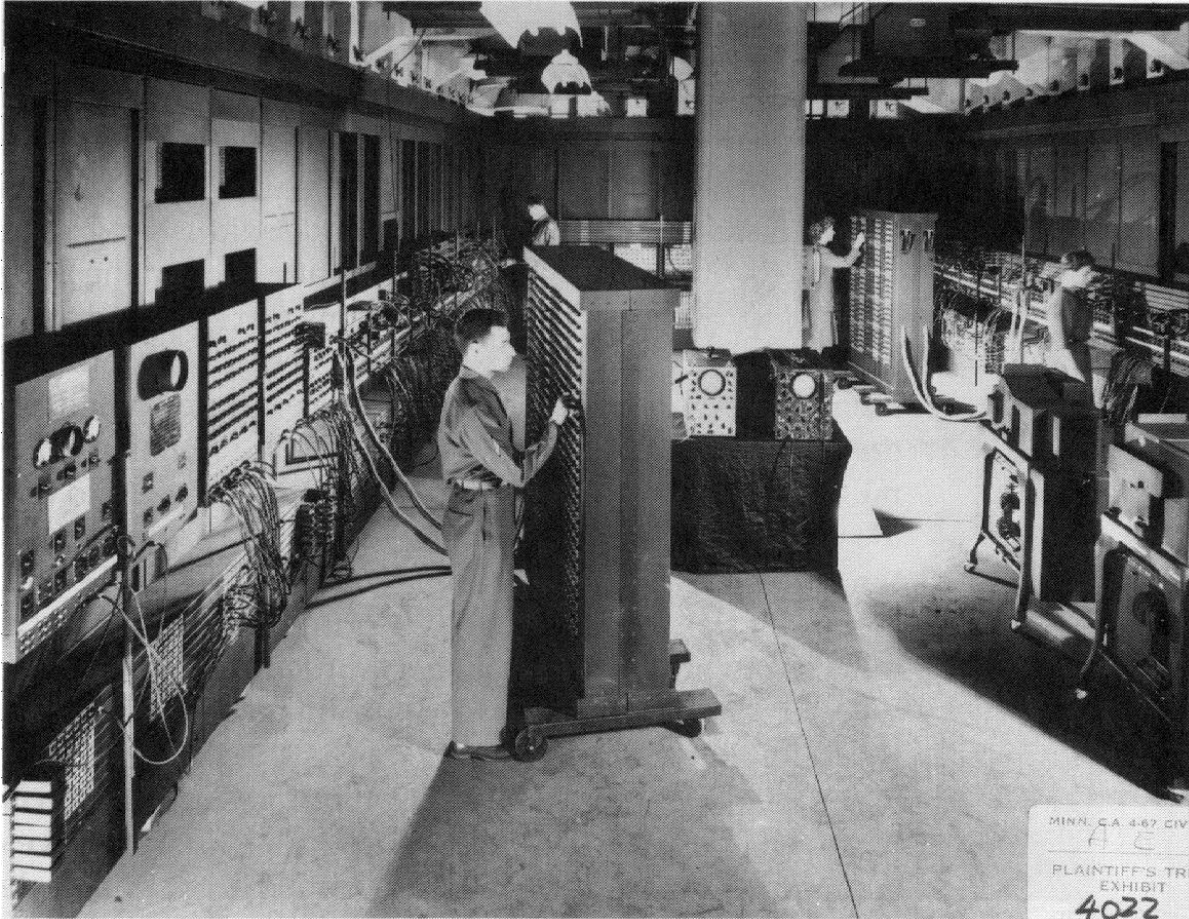
- Architectural simulation
- Logic simulation
- Circuit simulation (SPICE)
- Test verification

High Level VLSI Design Steps



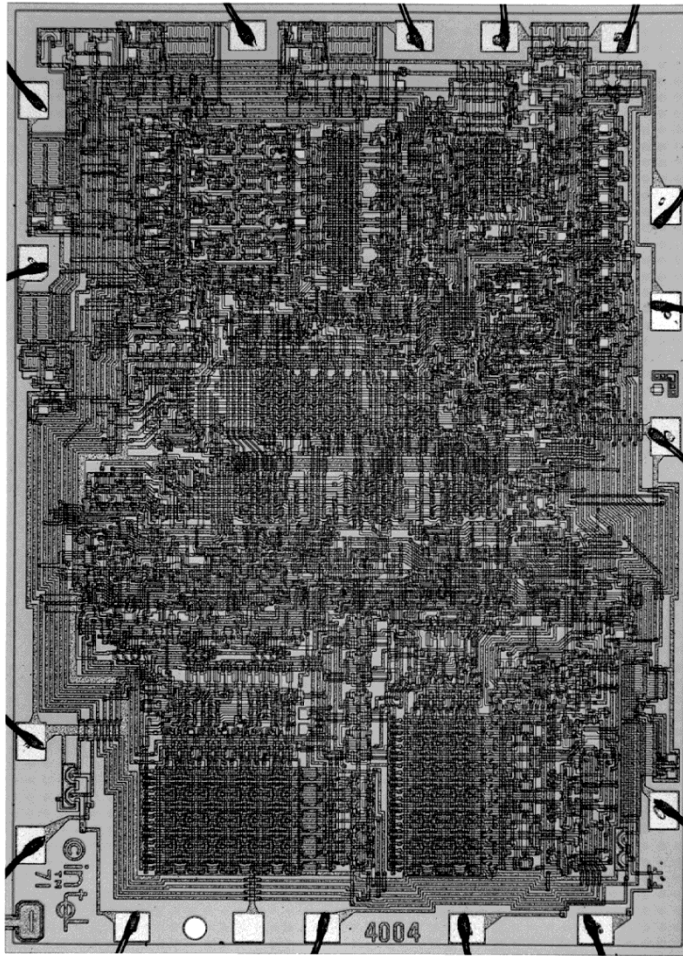
Introduction

Beginning of the Computer: ENIAC, the first electronic computer (1946)



- 333 integer multiplication/second
- A six-week run was equivalent to 100 person-years of manual computation
- Program resides in the wired connections

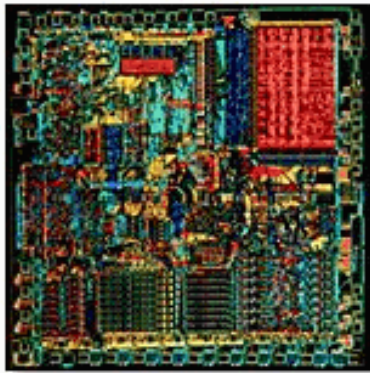
Intel 4004 Microprocessor



- 1971
- 10 μm NMOS-only
- 2300 transistors
- 1 MHz

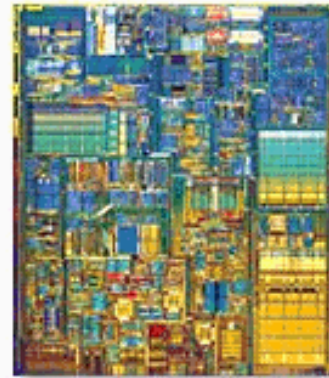
Intel Technology Advancement

Processor Comparison



Intel® i8088

Year: 1981
29,000 transistors



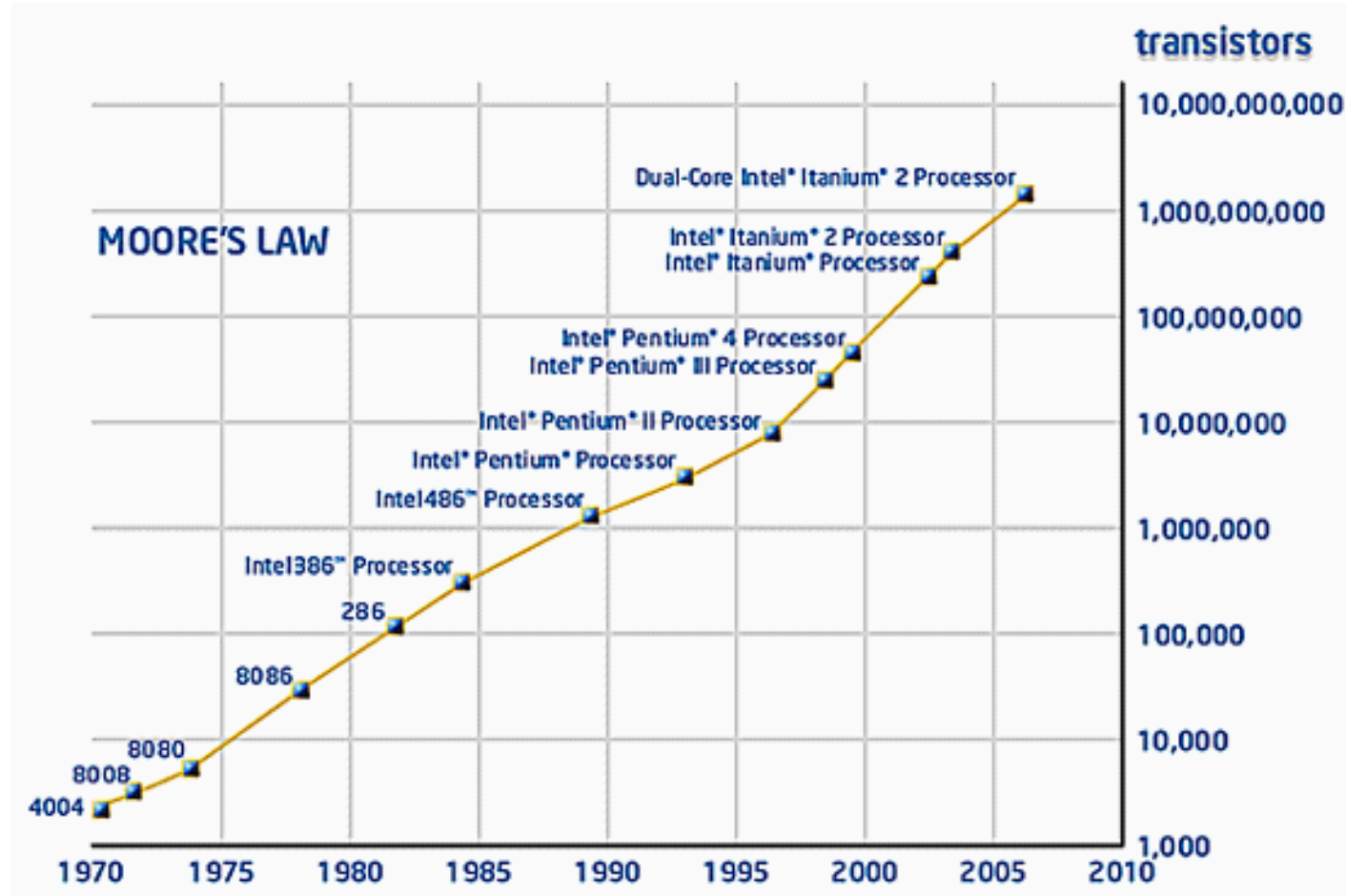
**Intel® Pentium® 4 Processor
with HT Technology**

Year: 2004
125,000,000 transistors

Moore's Law

- ❑ In 1965, Gordon Moore (founder of Intel) had a very interesting observation. He noticed that the number of transistors on a chip doubled every 18 to 24 months.
- ❑ He made a prediction that semiconductor technology would double its effectiveness every 18 months.

Moore's Law for Intel Microprocessors



Source: www.intel.com

Moore's Law in Travel Industry



1978

Approximate Cost: \$900

Approximate Travel Time: 7 hours

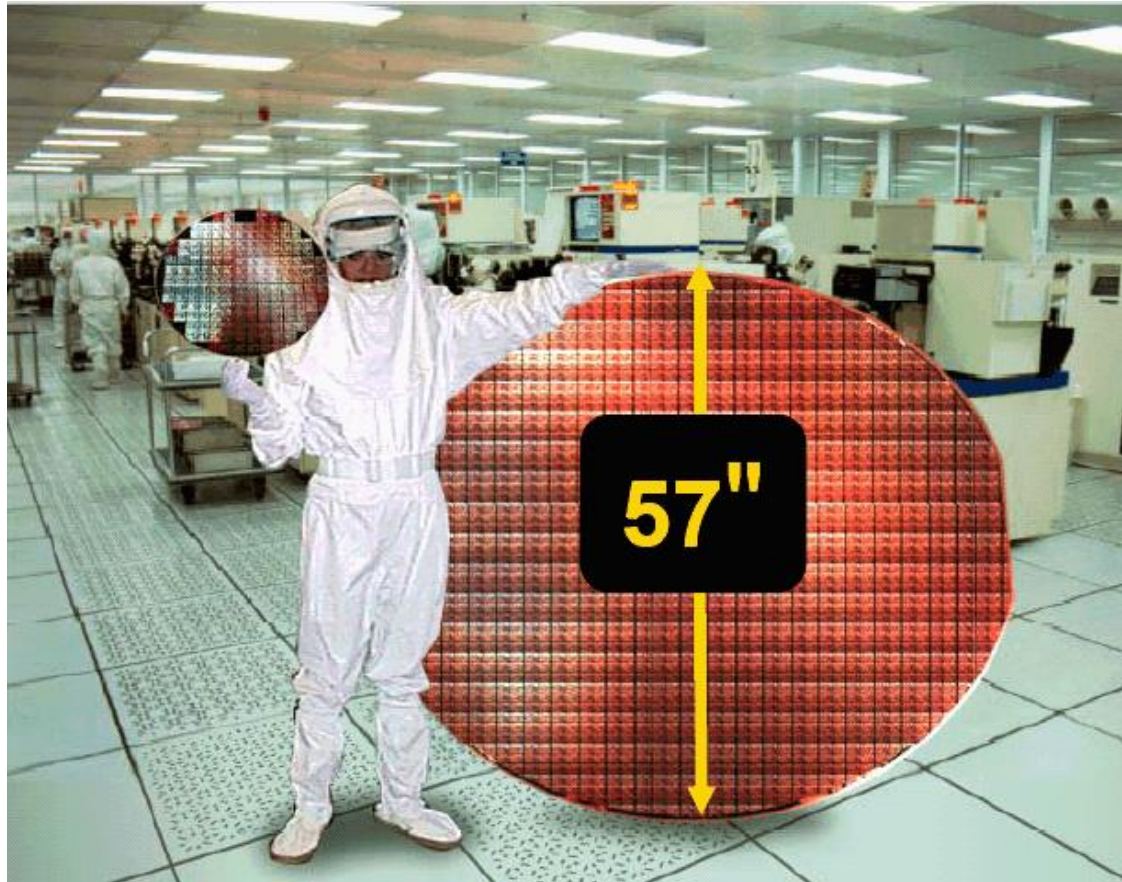


2003

Approximate Cost: 1¢

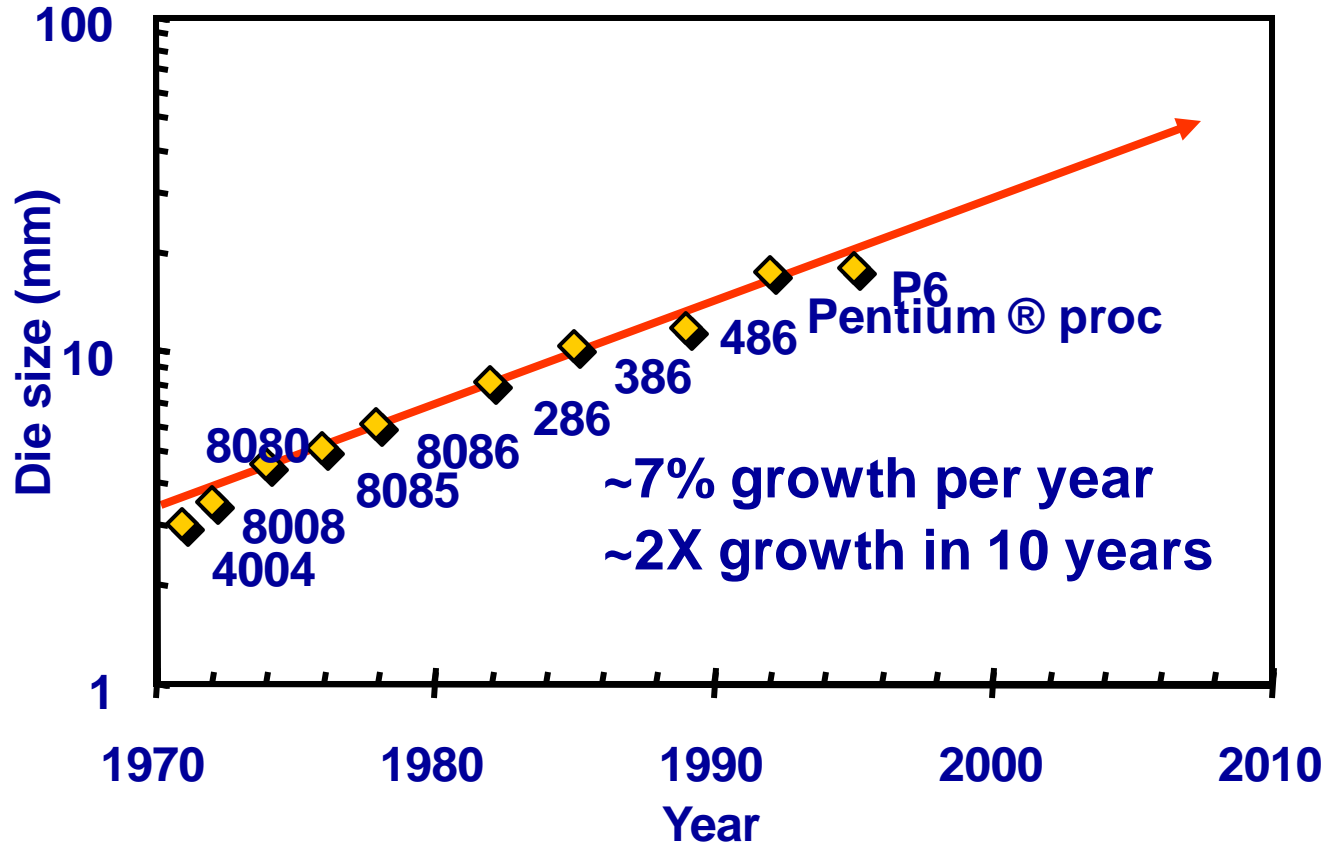
Approximate Travel Time: 1/4 second

Projected Wafer in 2000, circa 1975



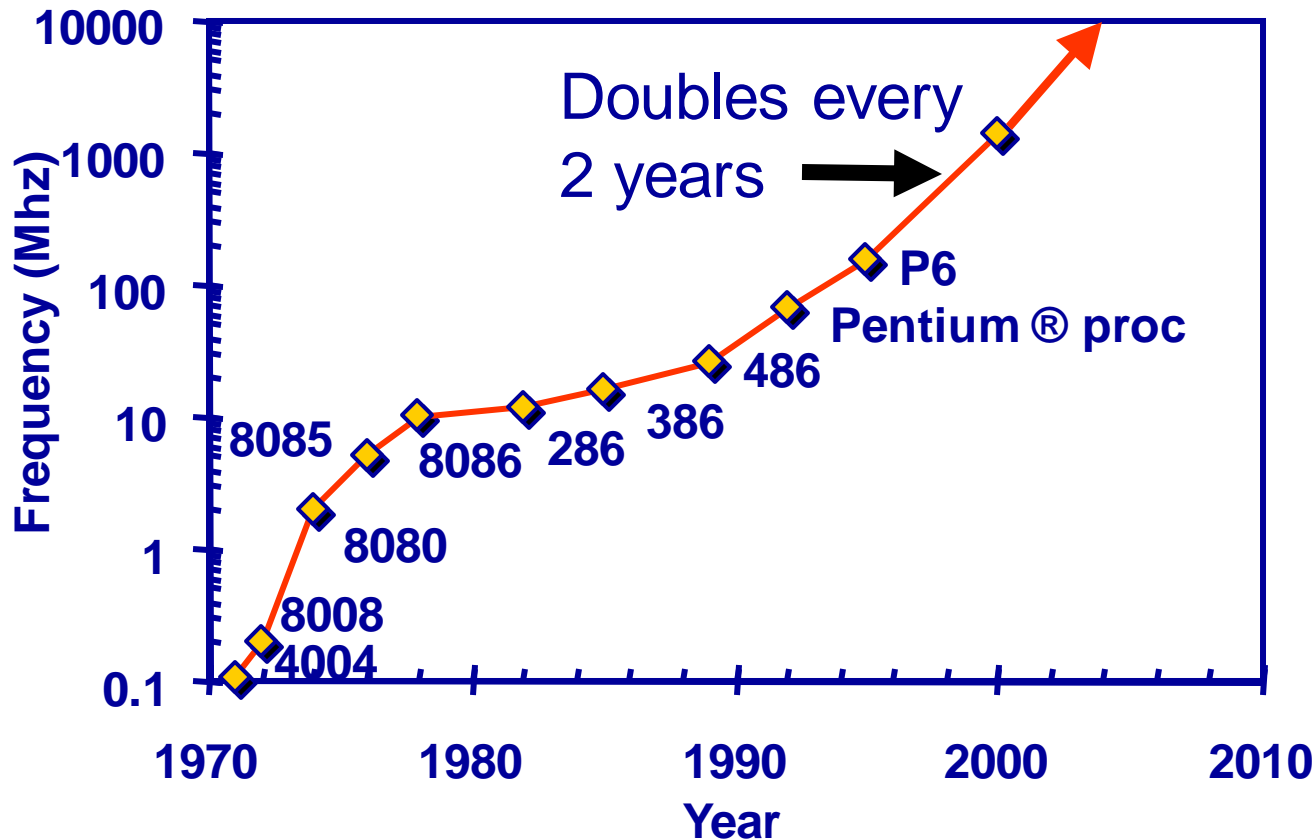
Moore was not always accurate

Die Size Growth



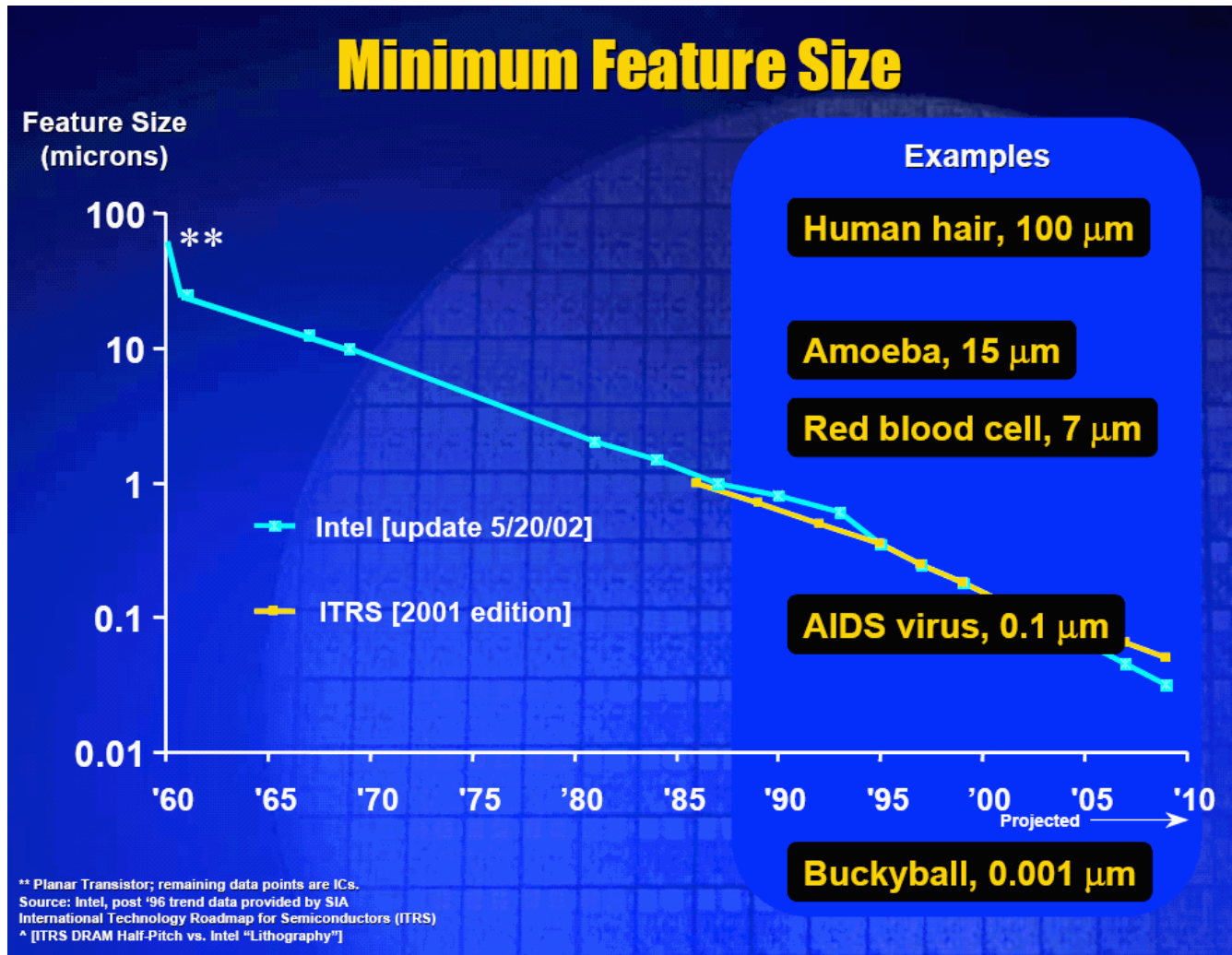
*Die size has grown by 14% to satisfy Moor's law, **BUT** the growth is almost stopped because of manufacturing and cost issues*

Clock Frequency



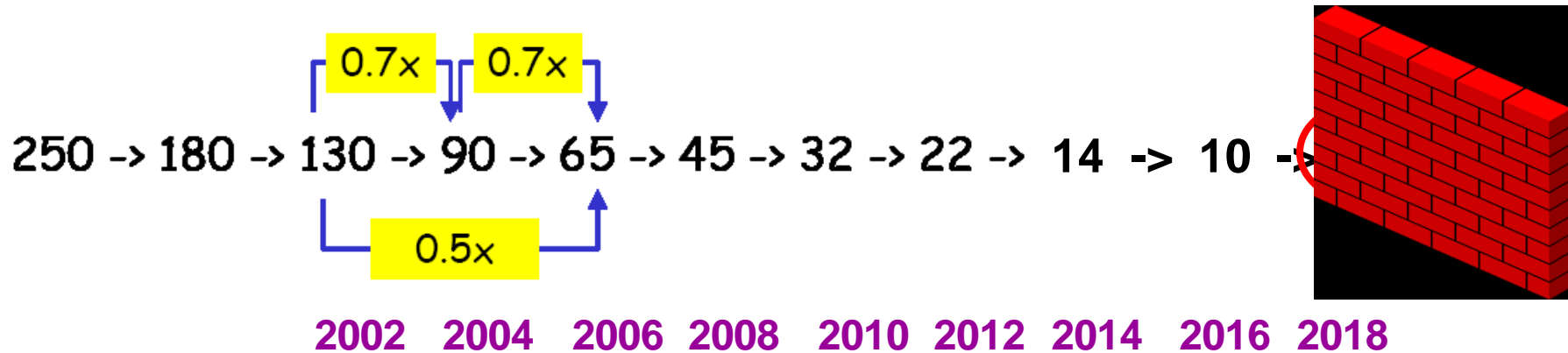
*Lead microprocessors frequency doubles every 2 year, **BUT** the growth is slower because of power dissipation issue*

CMOS Scaling Scenario

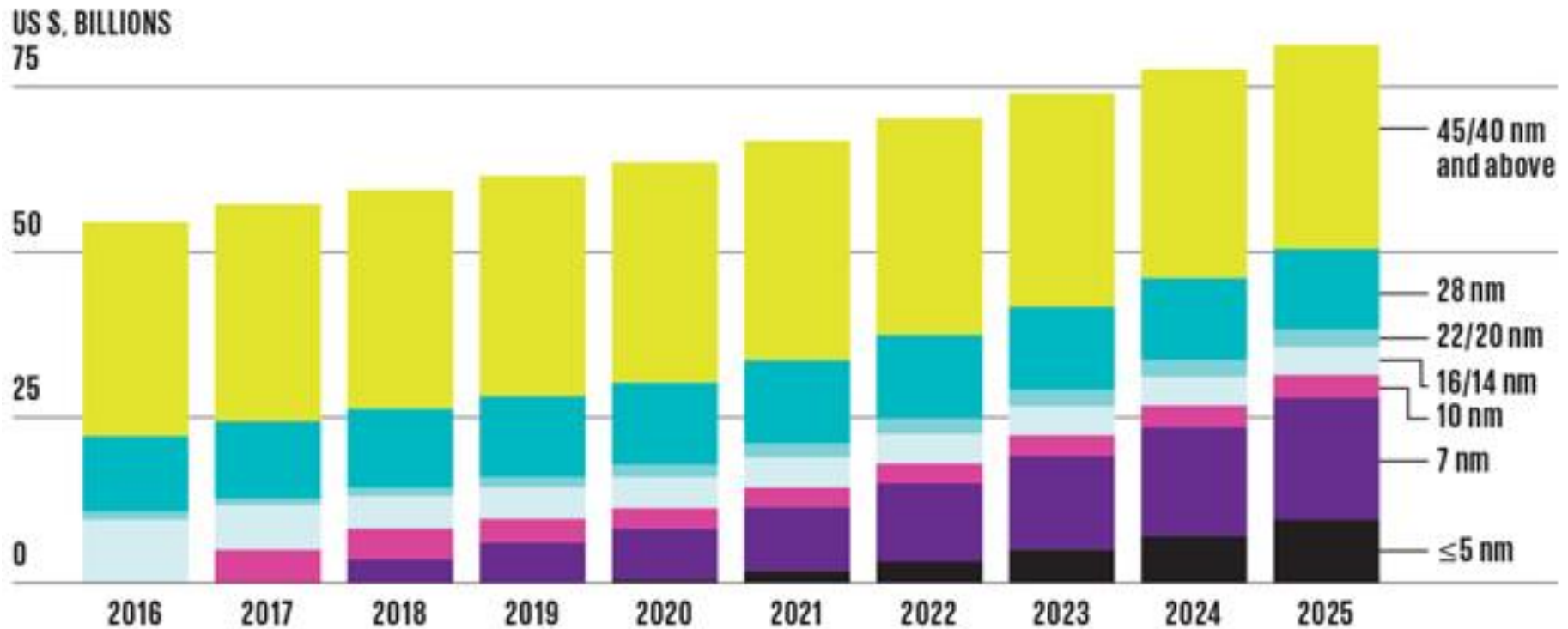


CMOS Scaling Calculation

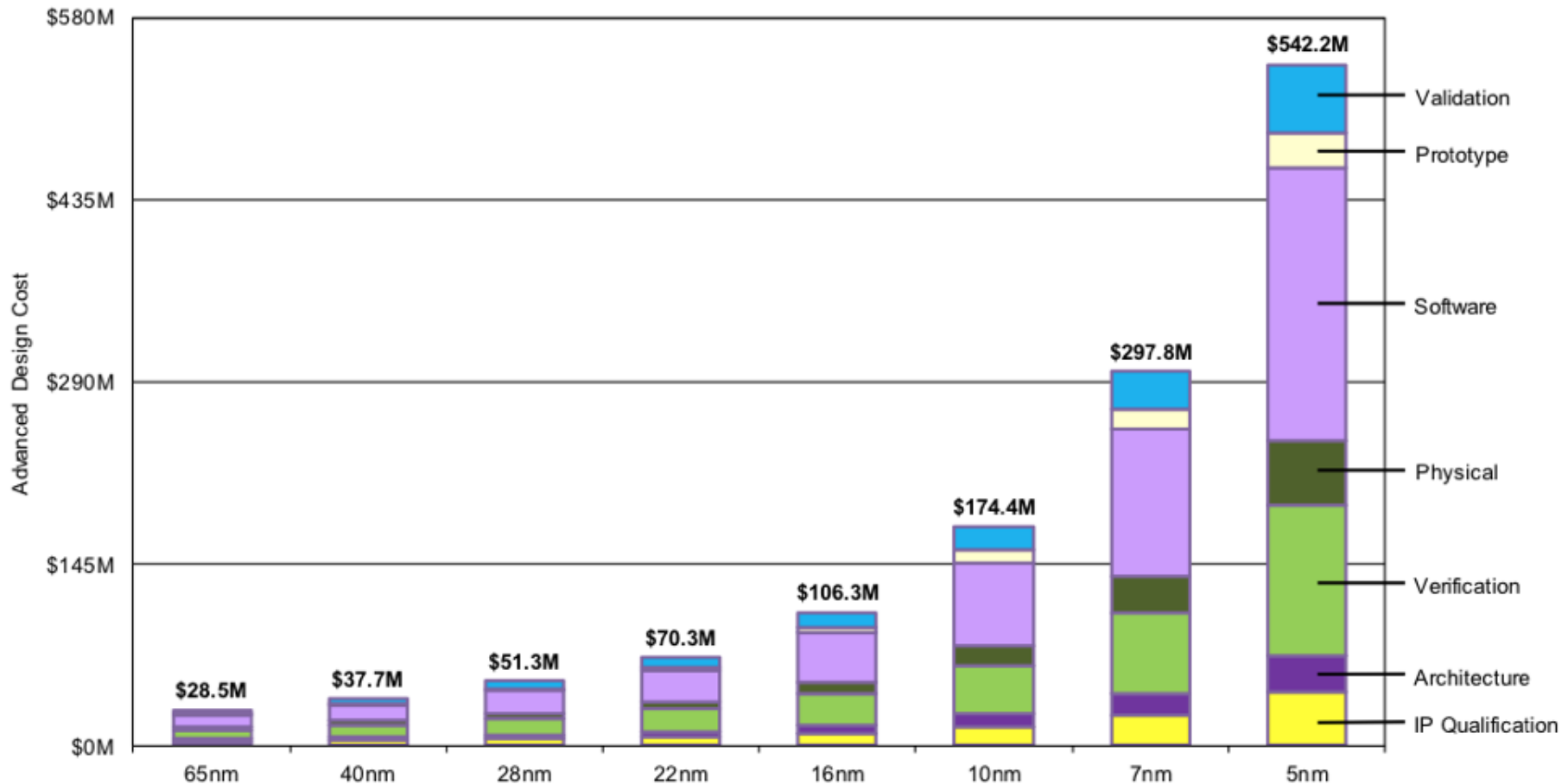
Scaling Calculator



The Evolution of Foundry Market

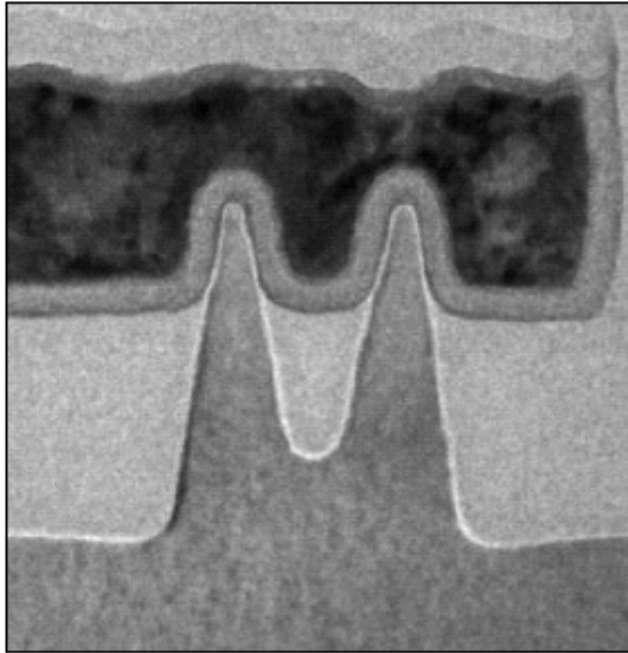


Cost of Design versus Technology Node

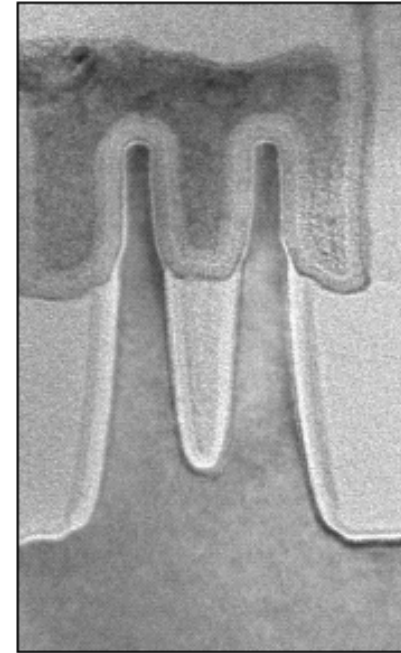


Intel's 22nm and 14nm Fin-FET Technology

Transistor Fin Improvement

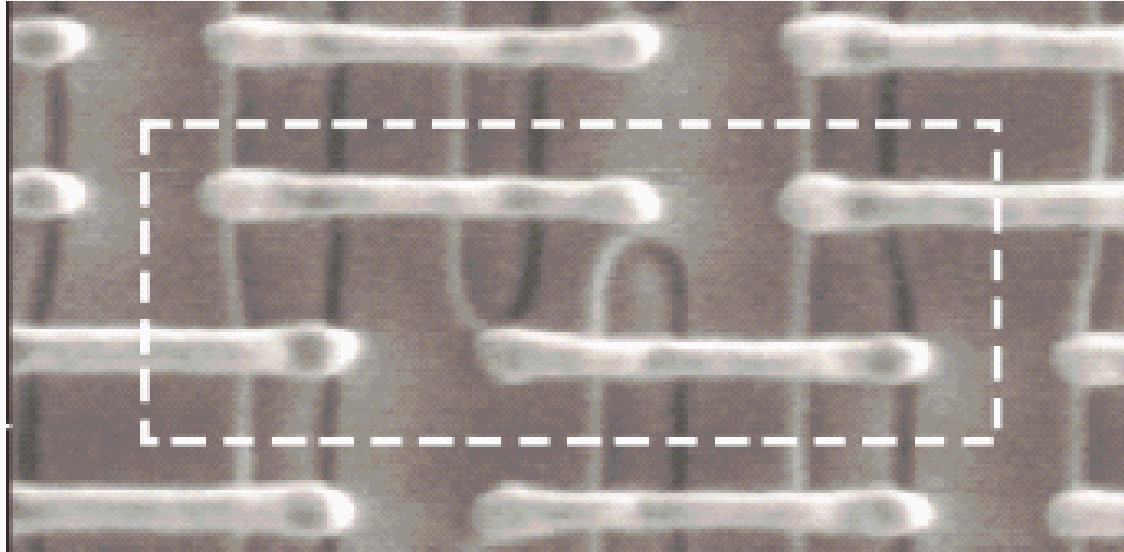


22 nm 1st Generation
Tri-gate Transistor



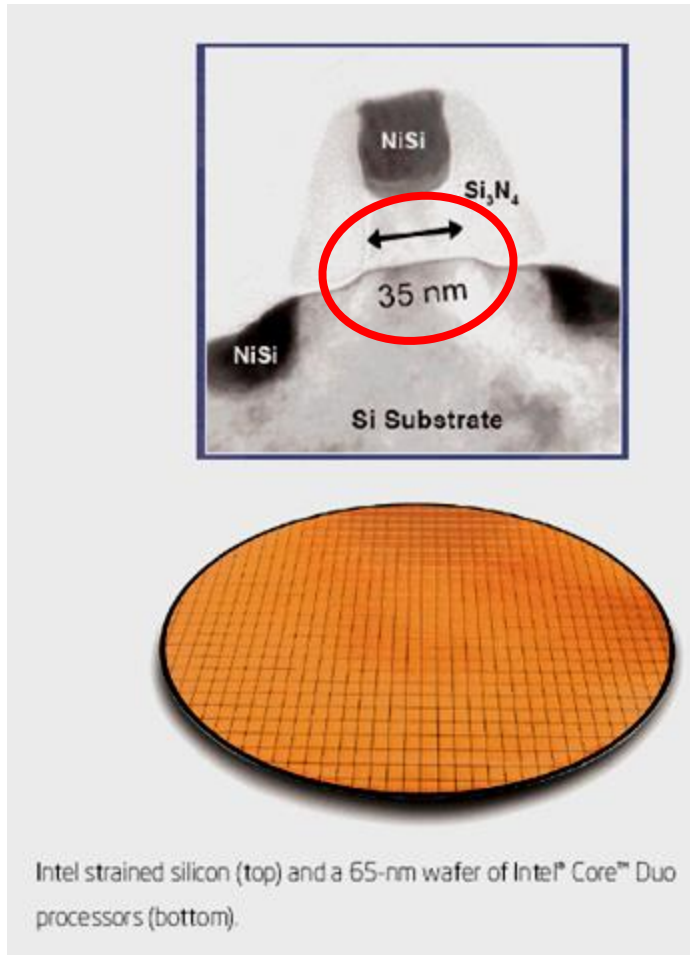
14 nm 2nd Generation
Tri-gate Transistor

65nm SRAM Memory Cell



10 million of these transistors could fit in a square millimeter – about the size of the tip of a ballpoint pen

MOS in 65nm of Core Due Processor

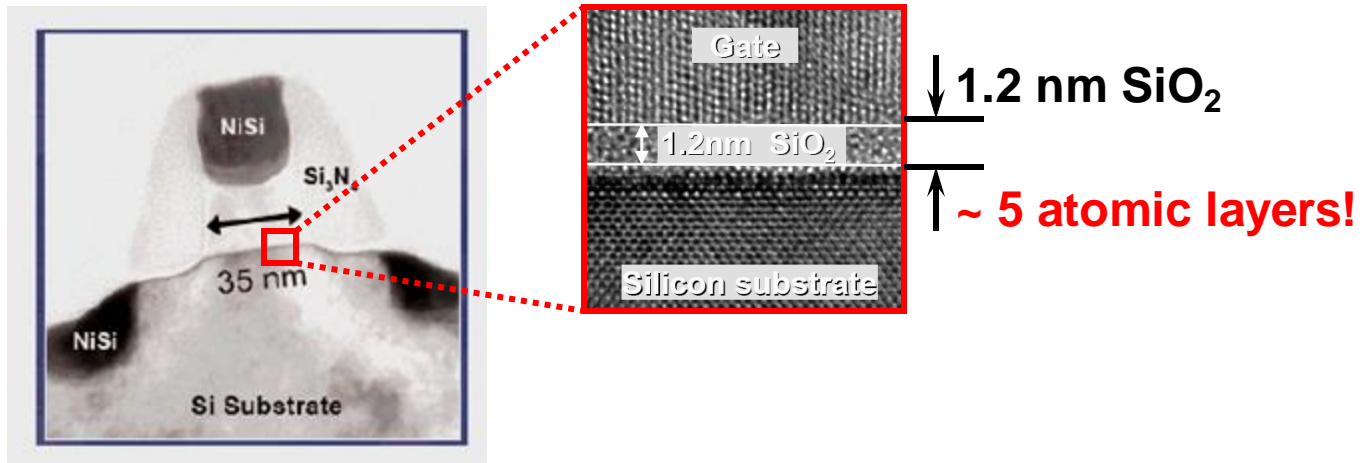


Distance between Si atoms = 5.43 °A

**No. of atoms in channel = 35 nm / 0.543 nm
= 64 Atoms!**

Problem: Uncertainty in transistor behavior and difficult to control variation!

Gate Insulator Thickness



Problem: Electrons can easily jump over the 5 atomic layers!

This is known as leakage current

Benefit of Smaller Transistors

- 1) More transistors in the same foot-print**
- 2) More functionality**
- 3) Reduced cost per function**
- 4) Faster devices and higher performance**
- 5) Lower switching energy per transistor**

Transistor Scaling Challenges

- 1) Feature sizes down to few atomic layers**
- 2) Increase uncertainty of transistor behavior**
- 3) Increase leakage power consumption**
- 4) Difficult to maintain performance enhancement**
- 5) Thermal limit issue**

New Method to Deal with Scaling

New Materials and Device Structures Extending Transistor Scaling

*Changes
Made*

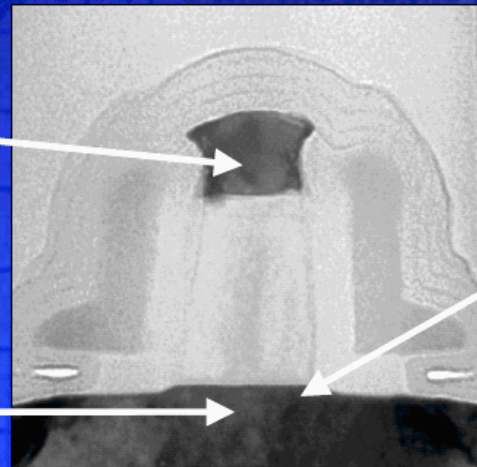
Gate
Silicide
Added

Channel
Strained
Silicon

*Future
Options*

High-k
Gate
Dielectric

New
Transistor
Structure

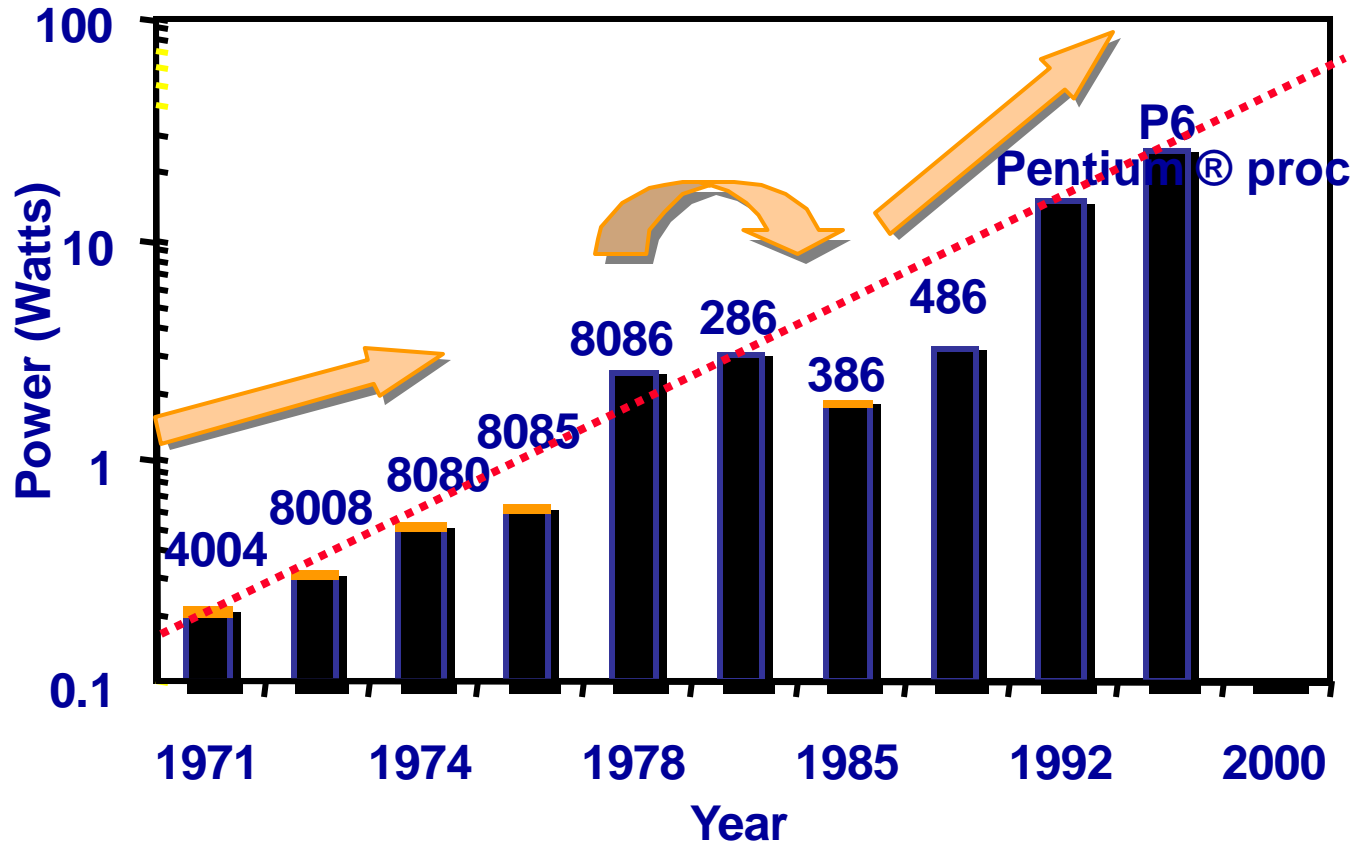


Transistor

Far-future Alternative Logic Devices

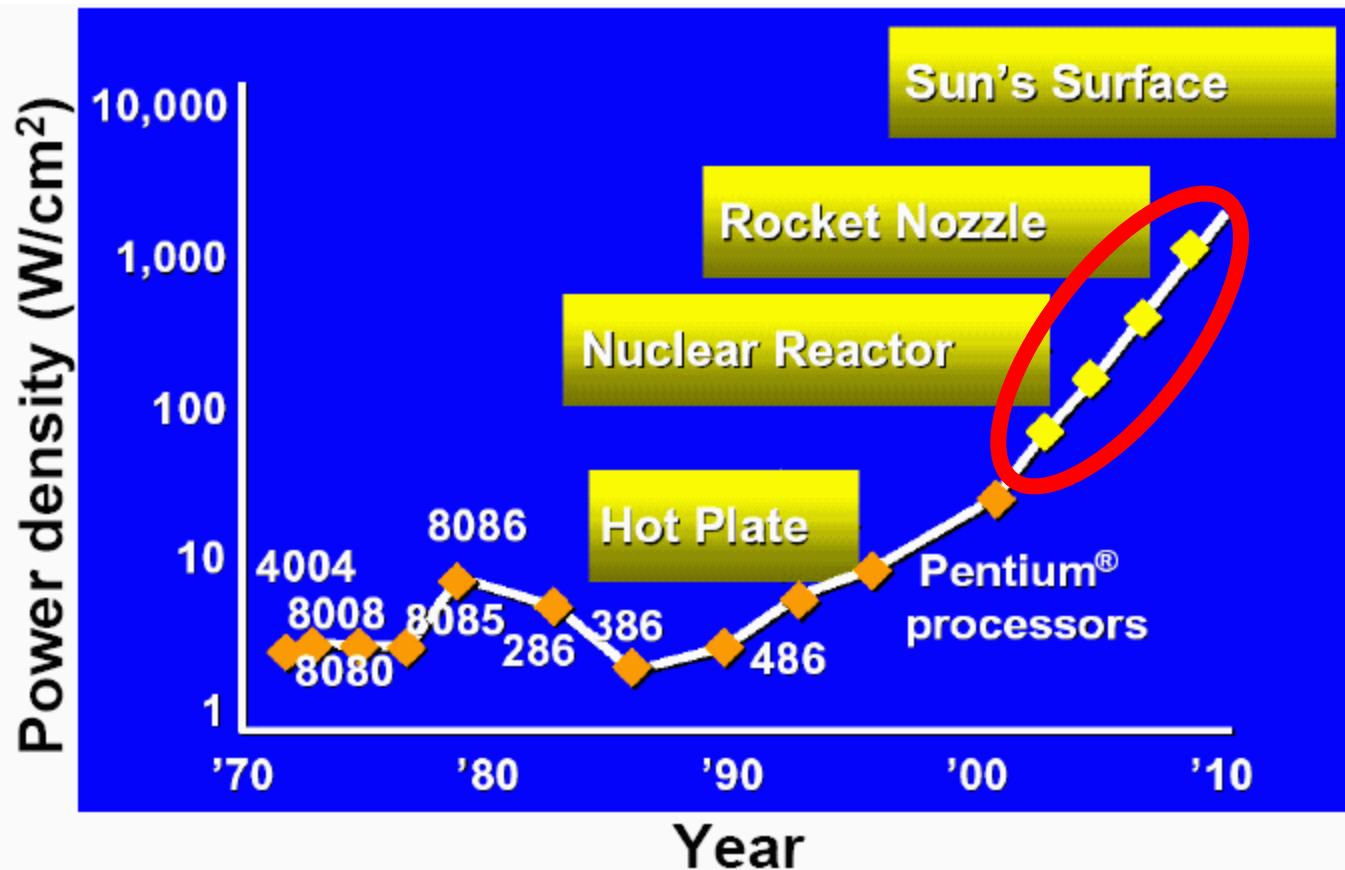
- 1) Spintronics (spin-based electronics)**
- 2) Quantum Computing**
- 3) DNA Computing**
- 4) Optical Computing**

Power Dissipation



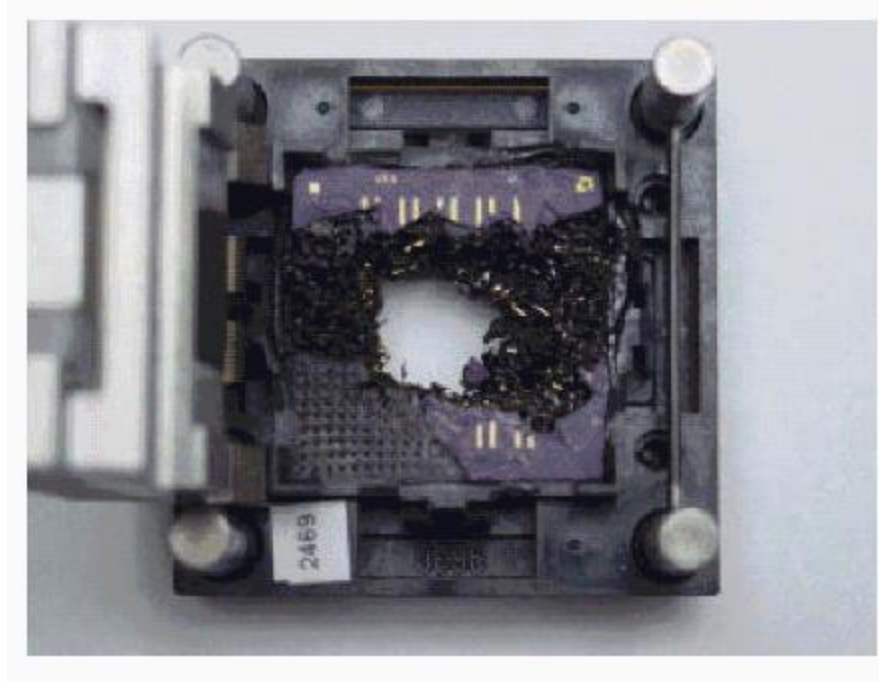
*Lead microprocessors power dissipation continue to increase, **BUT** it is getting too hard (and expensive) to keep up*

Power Density Problem

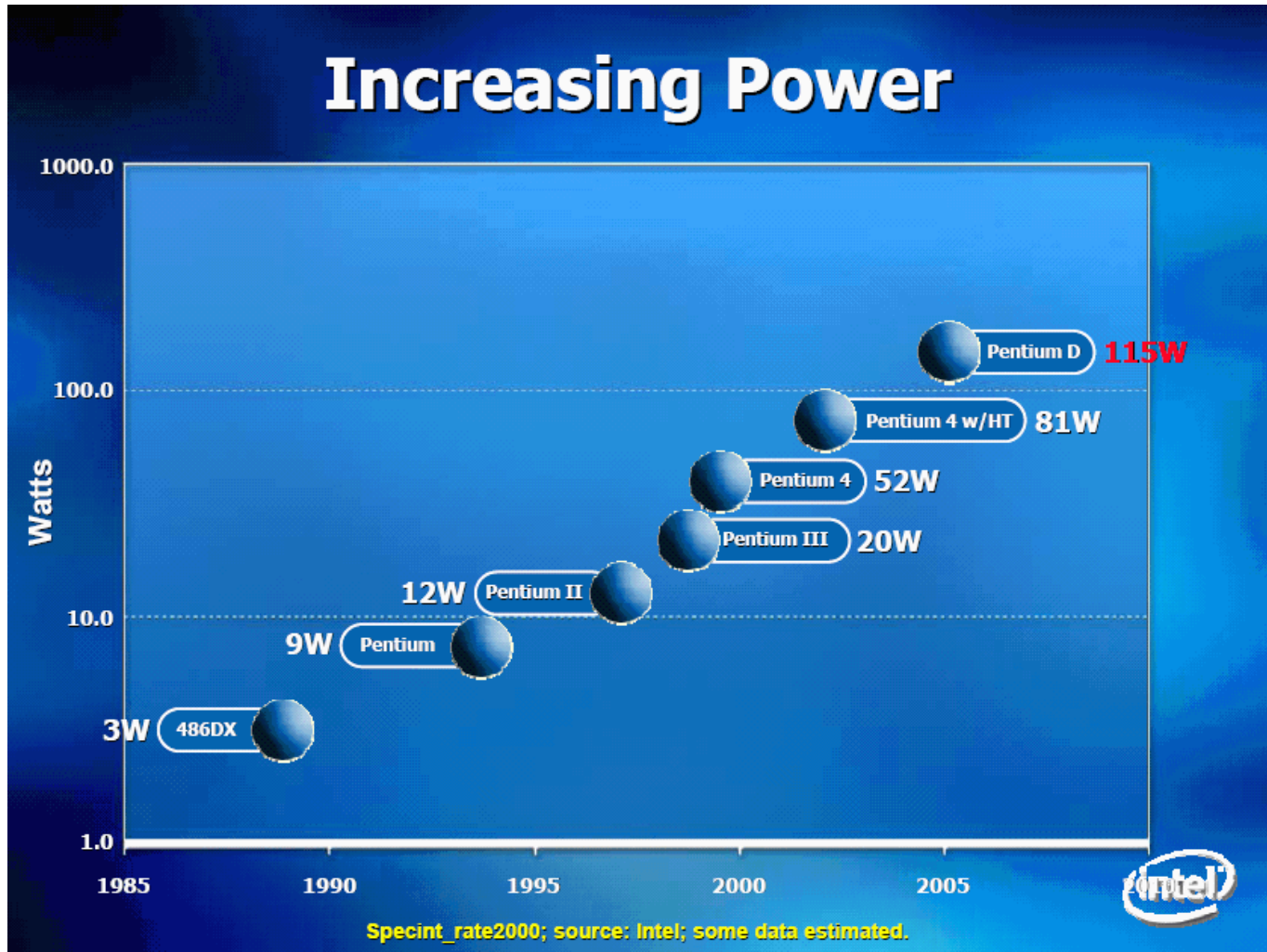


***Power density too high to keep junction at low temperature.
Power reaching limits of air cooling.***

Heat Management Consideration



Power Consumption Scenario



Some Calculations!

Power = 115 Watts

Supply Voltage = 1.2 V

Supply Current = $115 \text{ W} / 1.2 \text{ V} = 96 \text{ Amps!}$

Problem: Current density becomes a serious problem!

This is known as electromigration

Note: Fuses used for household appliances = 15 to 40 Amps

Another Calculations!

Power = 115 Watts

Chip Area = 2.2 Cm²

Heat Flux = 115 W / 2.2 Cm² = 50 W/Cm² !

Problem: Heat flux is another serious issue!

Notes:

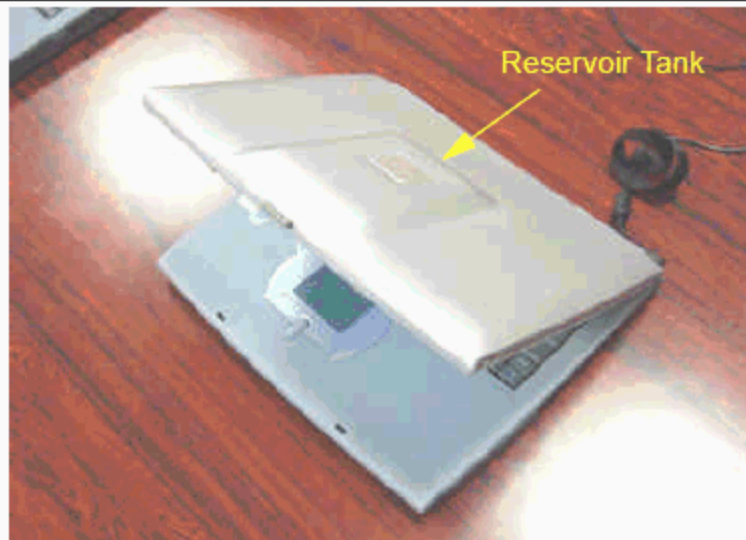
Heat flux in iron = 0.2 W/Cm²

Heat flux in frying pan = 10 W/Cm²

Method of Heat Management

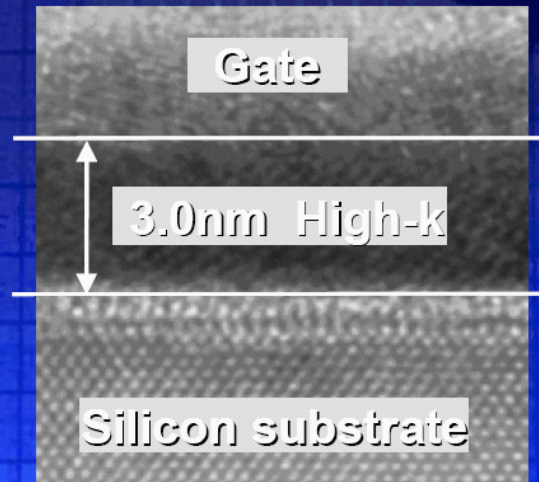
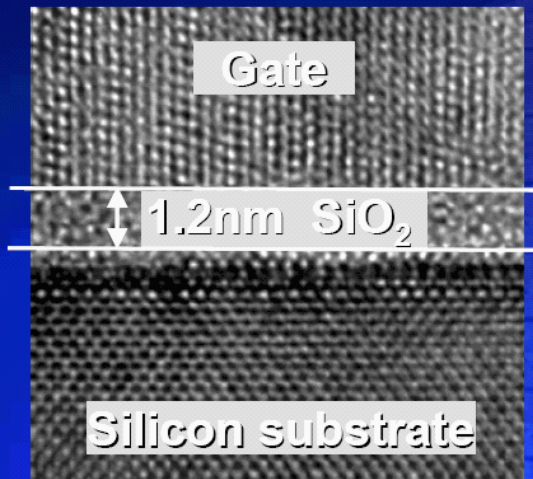
- 1) Proper heat removal system (expensive)**
- 2) Improve manufacturing for low power MOS**
- 3) Architectural solutions (multi-cores)**

Hitachi Water Cooling Laptop



Manufacturing Solution

High K for Gate Dielectrics



	90nm process	Experimental high-k
Capacitance	1X	1.6X
Leakage	1X	< 0.01X

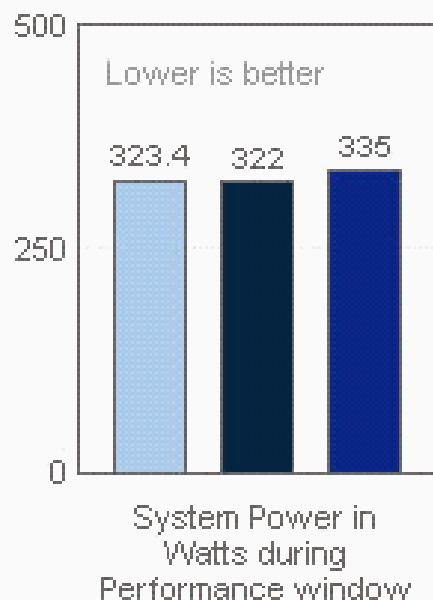
Source: Intel

Architectural Solution

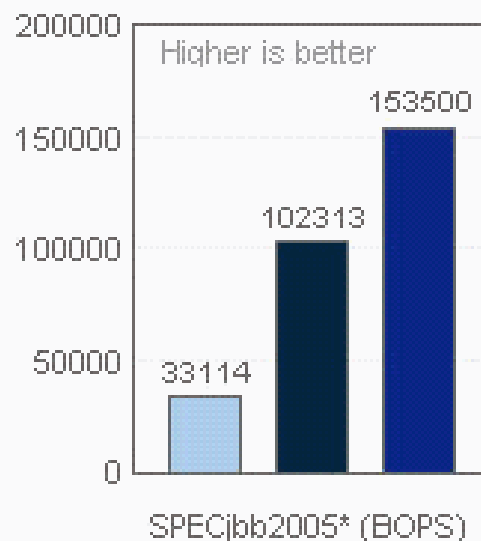


Architectural Solution

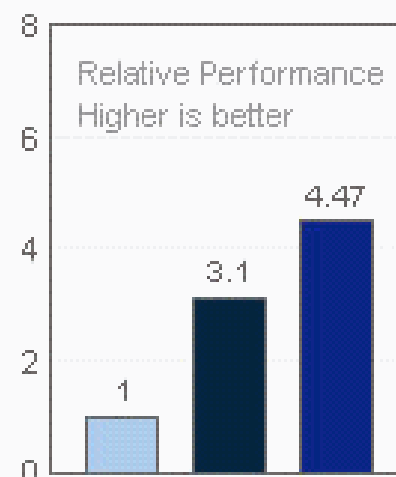
Same Power Envelope



Higher Performance

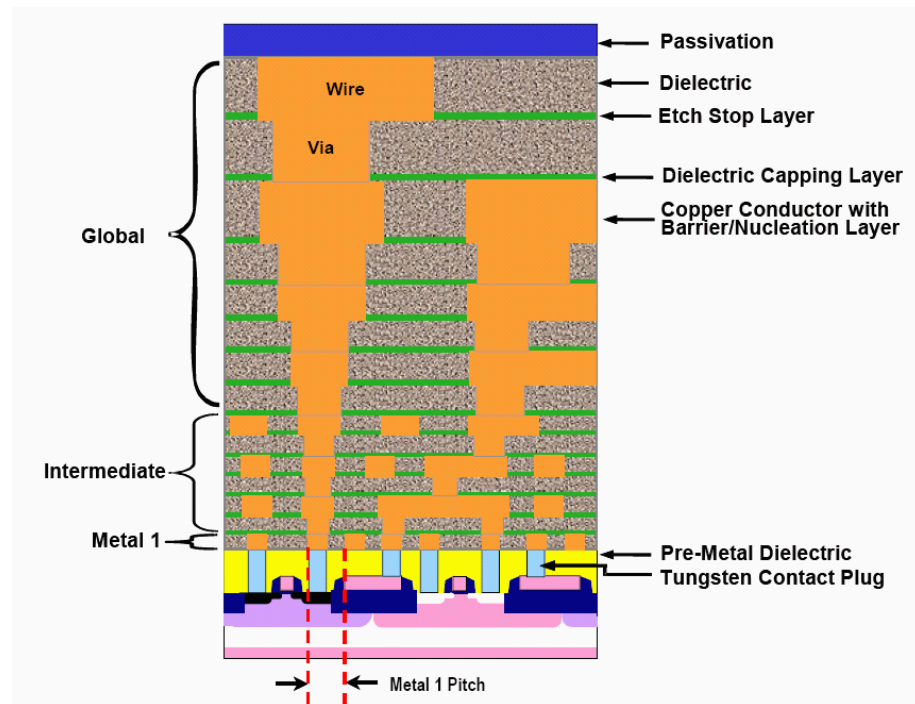


Superior Perf/Watt

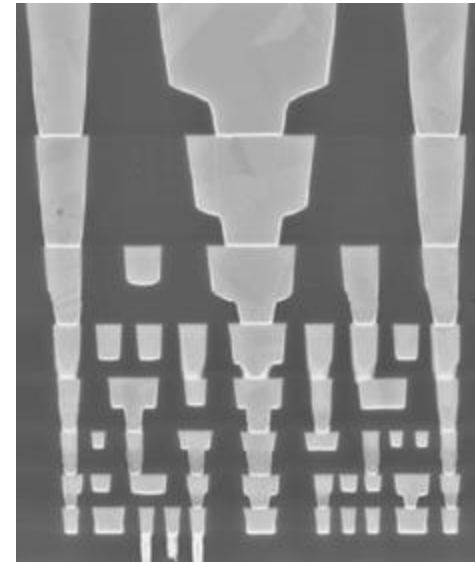


- Intel® Xeon® Processor (3.60 GHz 2MB L2 Cache, 800 MHz bus)
- Dual-Core Intel® Xeon® Processor 5160 (3.00 GHz 4MB L2 Cache, 1333 MHz bus)
- Quad-Core Intel® Xeon® Processor E5345 (2.33 GHz 2x4MB L2 Cache 1333 MHz FSB)

Interconnect Architecture



Metal stack over Silicon

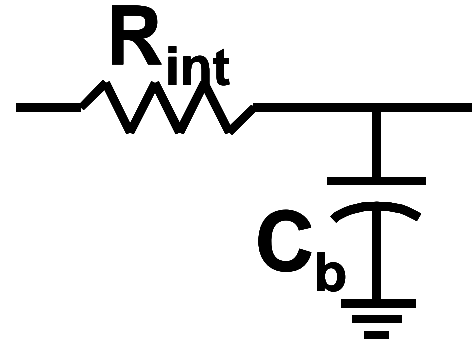


Real wiring cross section photograph

Interconnect Scaling Scenario

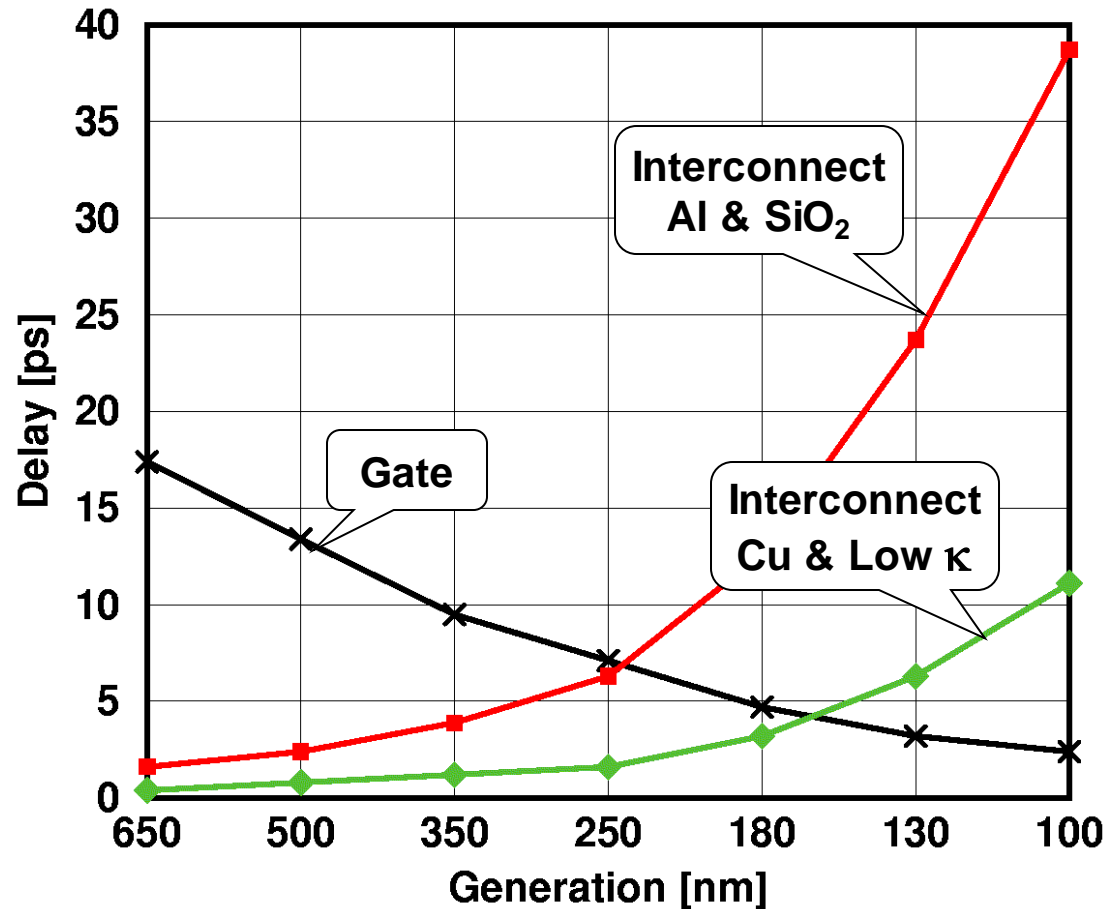
Technology	45 nm (2008)	35 nm (2010)	22 nm (2012)
Wire width	45 nm	32 nm	22 nm
Wire Thickness	80 nm	60 nm	40 nm
Total Number of Wires	150 Million	300 Million	600 Million
Total wire length	1.4 mile	2 mile	2.8 mile

Delay versus Interconnect Scaling



$$\text{Delay} \propto R_{int} C_b$$

Interconnect versus Gate Delay



[Bohr, IEDM '95]

Al	3.0 μΩ cm
Cu	1.7 μΩ cm
SiO ₂	κ = 4.0
Lowκ	κ = 2.0
Al & Cu	0.8 μ Thick
Al & CU Line	43 μ Long

Interconnect Challenges

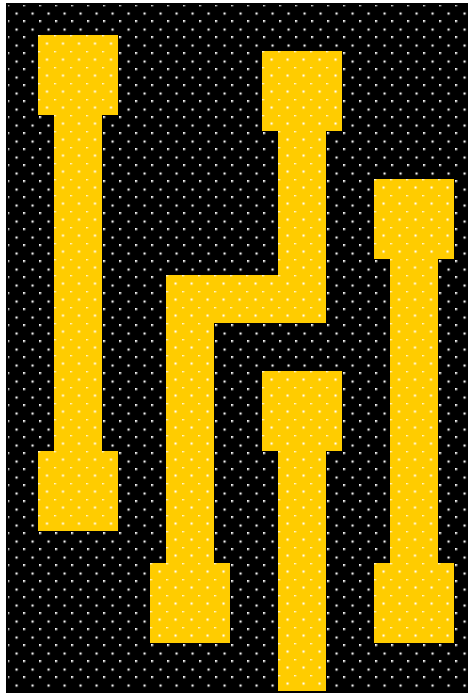
- 1) Slows down with scaling**
- 2) Consume more power**
- 3) Generate more heat**
- 4) Electromigration**

Far-future Alternative Interconnects

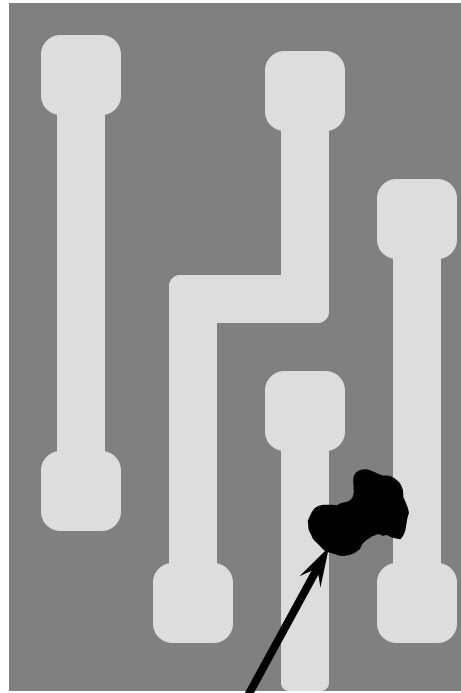
- 1) Carbon nanotubes**
- 2) Optical Interconnect**
- 3) Molecular wires**
- 4) Spintronics interconnect system**

Process Defects and Yield Loss

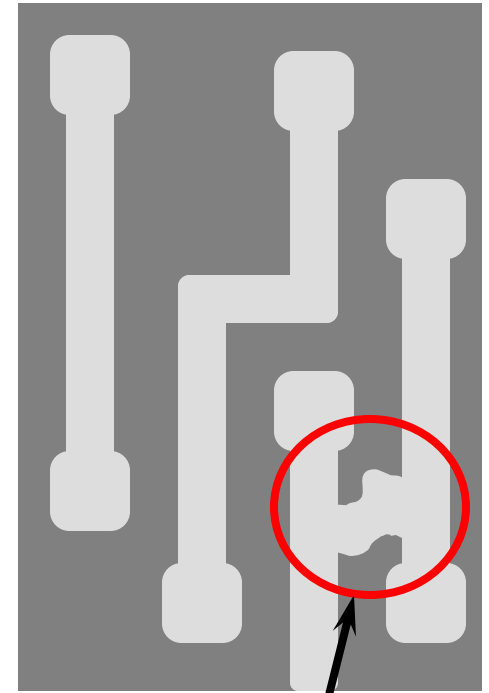
Process Defect Causing Fault (Short)



Original layout



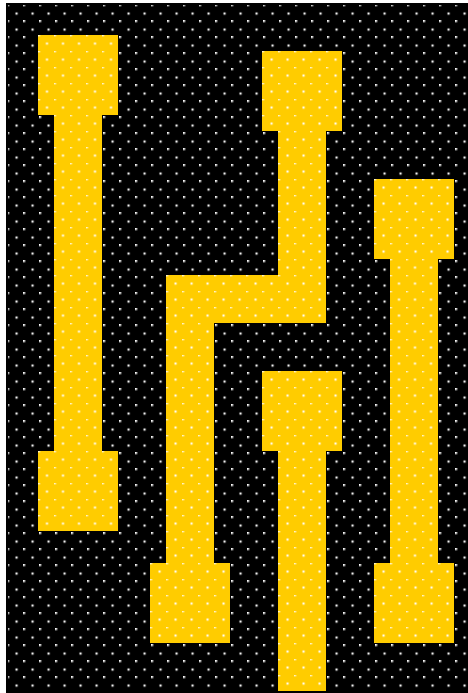
A particle or
a process defect



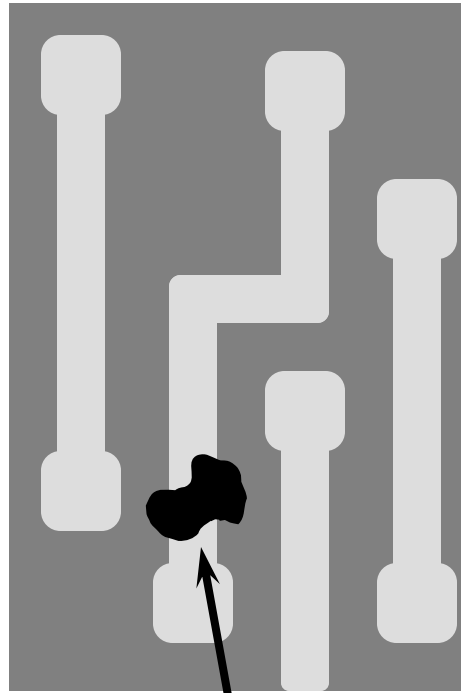
Short defect

Process Defects and Yield Loss

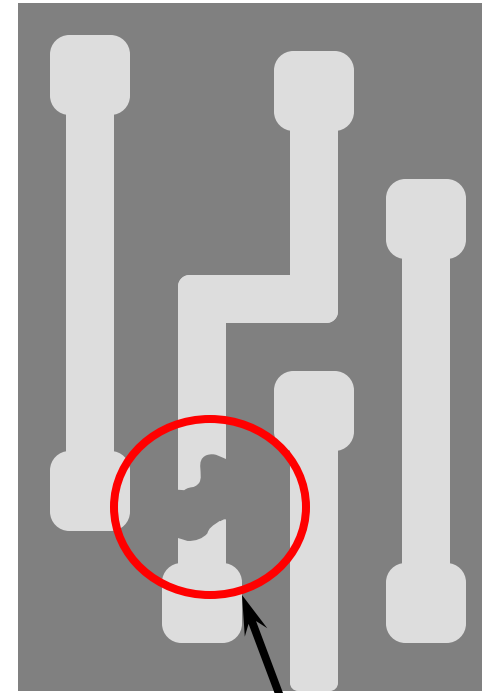
Process Defect Causing Fault (Opens)



Original layout

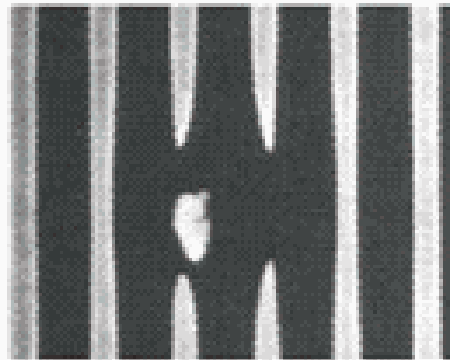
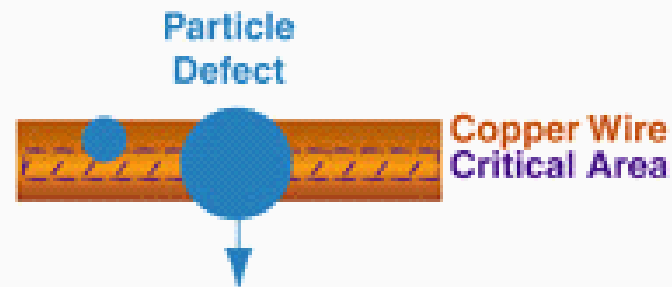


A particle or
a process defect

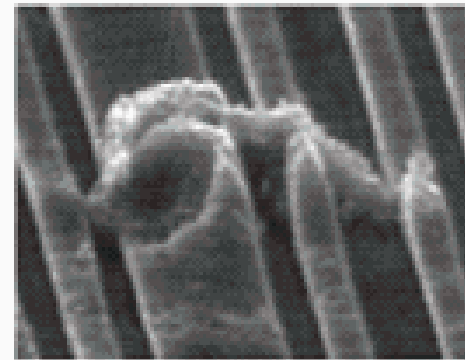
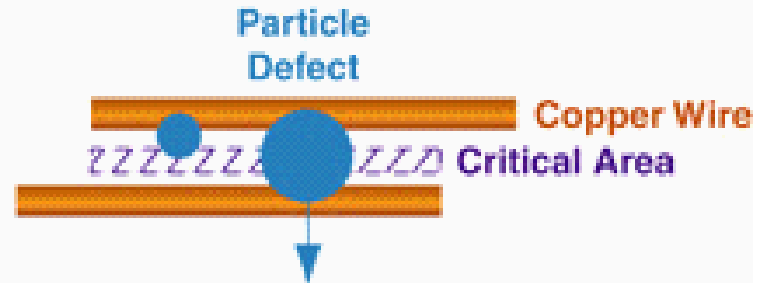


open defect

Process Defect Photograph



Open Circuit

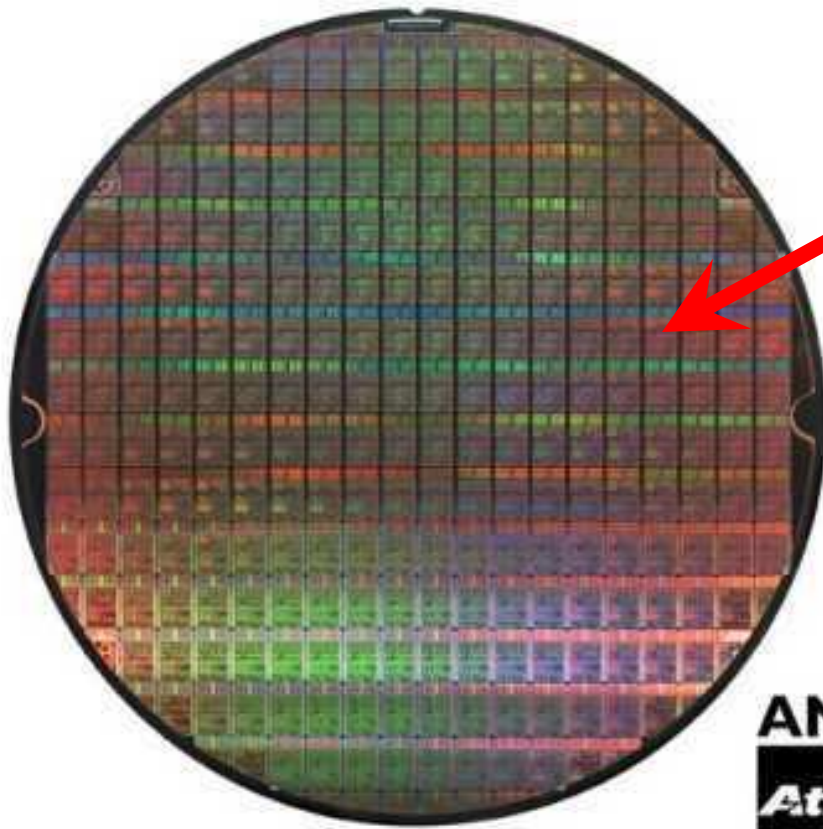


Short Circuit

Manufacturing Issues

- 1) Smaller feature size requires ultra-clean manufacturing facility (expensive)**
- 2) Because of the increase in complexity, defects could drastically reduces the manufacturing yield (% of working chips)**
- 3) There are much more issues related to “Design for Manufacturability” (DFM)**

Die Cost



**Single
die**

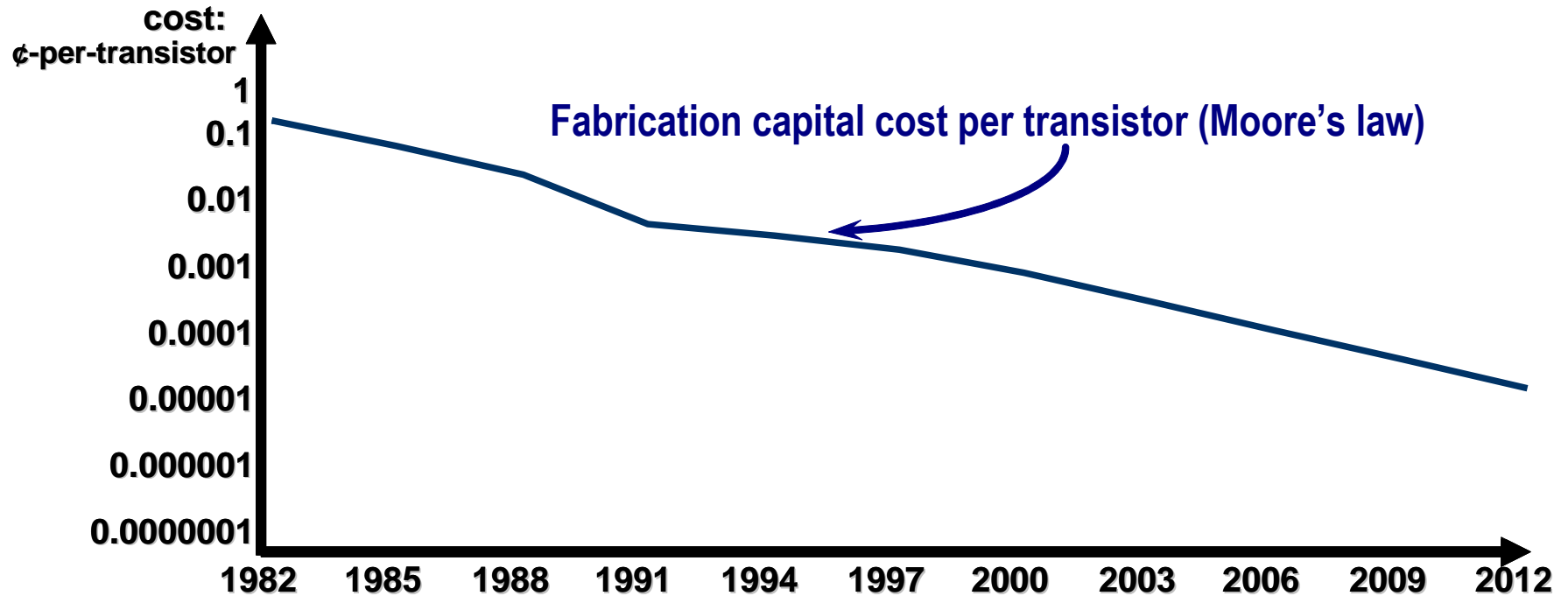
Wafer



Going up to 12" (30cm)

From <http://www.amd.com>

Cost per Transistor



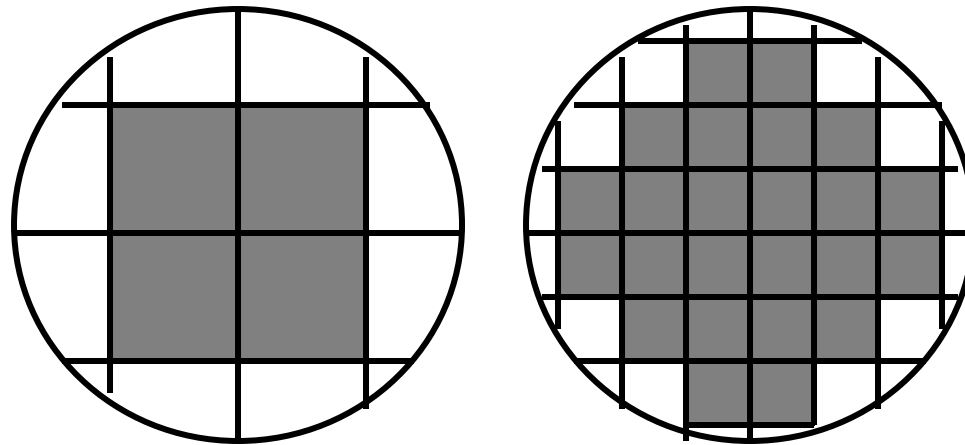
Cost per transistor is reducing exponentially following Moore's law.

Yield

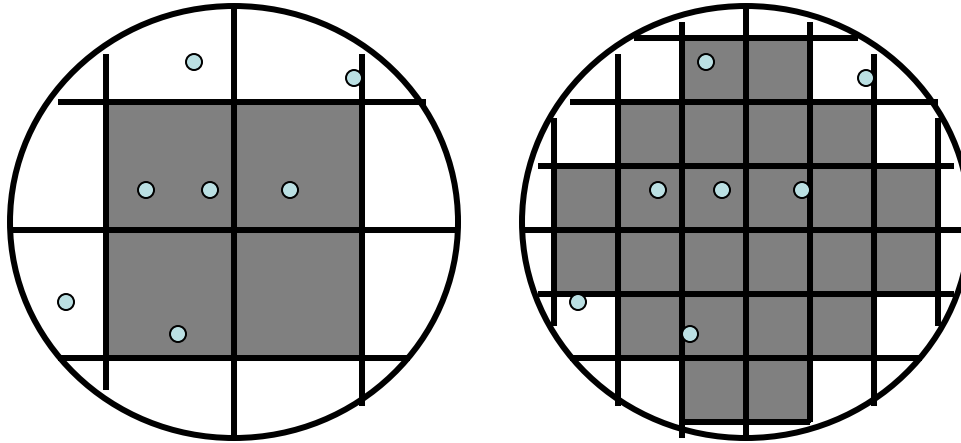
$$Y = \frac{\text{No. of good chips per wafer}}{\text{Total number of chips per wafer}} \times 100\%$$

$$\text{Die cost} = \frac{\text{Wafer cost}}{\text{Dies per wafer} \times \text{Die yield}}$$

$$\text{Dies per wafer} = \frac{\pi \times (\text{wafer diameter}/2)^2}{\text{die area}} - \frac{\pi \times \text{wafer diameter}}{\sqrt{2} \times \text{die area}}$$



Defects and Die Cost



$$\text{die yield} = \left(1 + \frac{\text{defects per unit area} \times \text{die area}}{\alpha} \right)^{-\alpha}$$

α is approximately 3

$$\text{die cost} = f(\text{die area})^4$$

Some Examples (1994)

Chip	Metal layers	Line width	Wafer cost	Def./cm ²	Area mm ²	Dies/wafer	Yield	Die cost
386DX	2	0.90	\$900	1.0	43	360	71%	\$4
486 DX2	3	0.80	\$1200	1.0	81	181	54%	\$12
Power PC 601	4	0.80	\$1700	1.3	121	115	28%	\$53
HP PA 7100	3	0.80	\$1300	1.0	196	66	27%	\$73
DEC Alpha	3	0.70	\$1500	1.2	234	53	19%	\$149
Super Sparc	3	0.70	\$1700	1.6	256	48	13%	\$272
Pentium	3	0.80	\$1500	1.5	296	40	9%	\$417

Summary

Digital IC Business is Unique

Things Get Better Every Few Years

Companies Have to Stay on Moore's Law Curve to Survive

Benefits of Transistor Scaling

Higher Frequencies of Operation

Massive Functional Units, Increasing On-Die Memory

Cost/Functionality Going Down

Downside of Transistor Scaling

Power (Dynamic and Static)

Design and Manufacturing Cost

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